

FIG. 1A

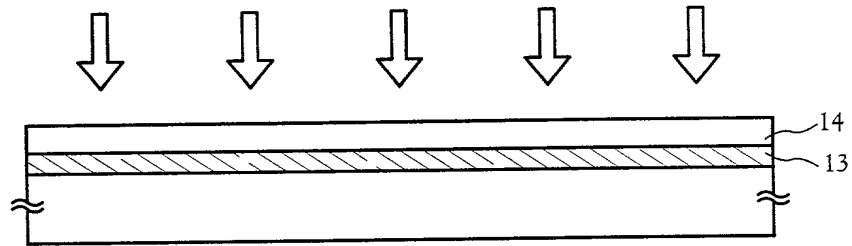


FIG. 1B

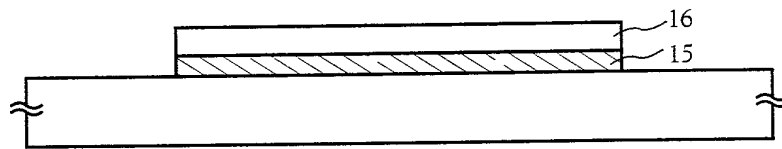


FIG. 1C

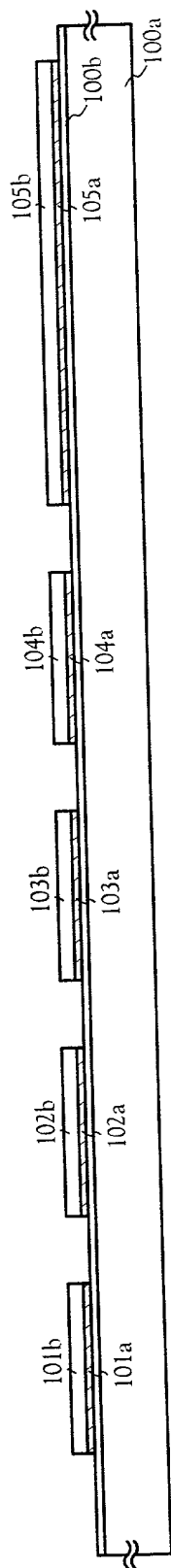


FIG. 2A

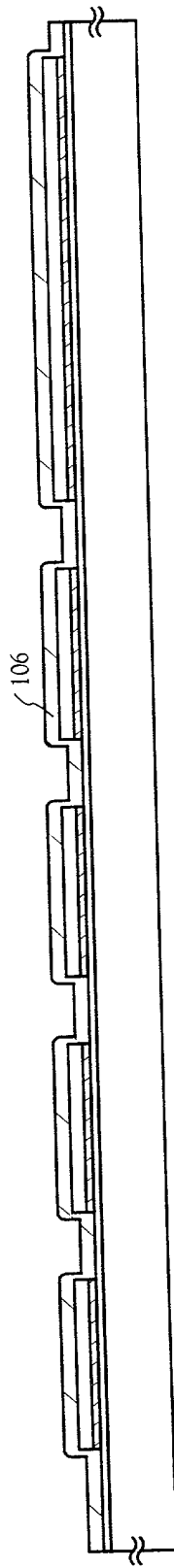


FIG. 2B

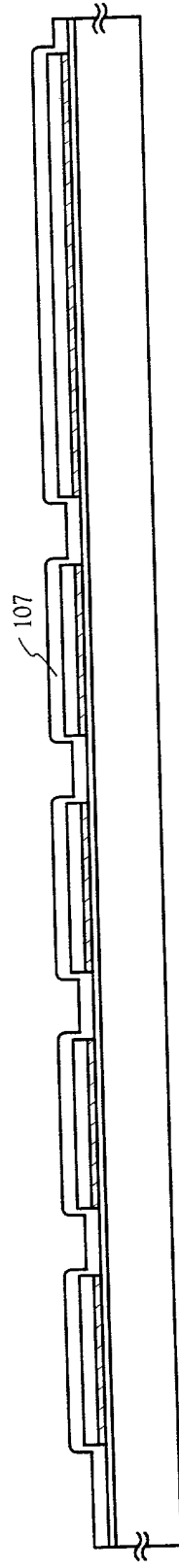


FIG. 2C

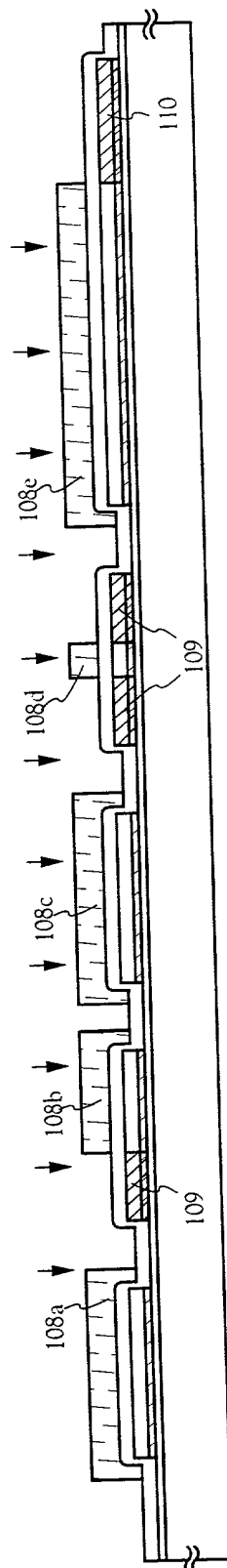


FIG. 2D

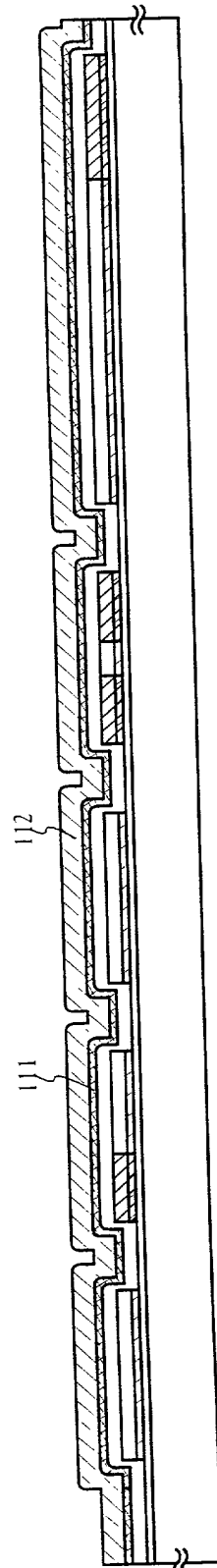


FIG. 2E

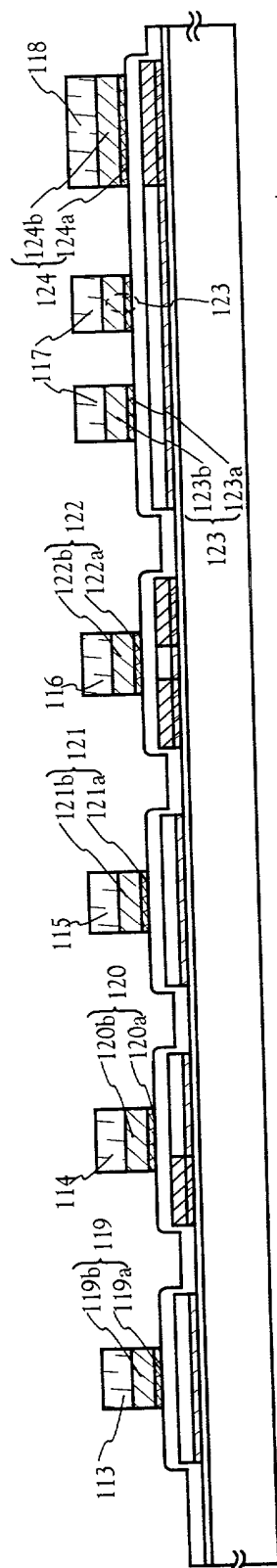


FIG. 3A

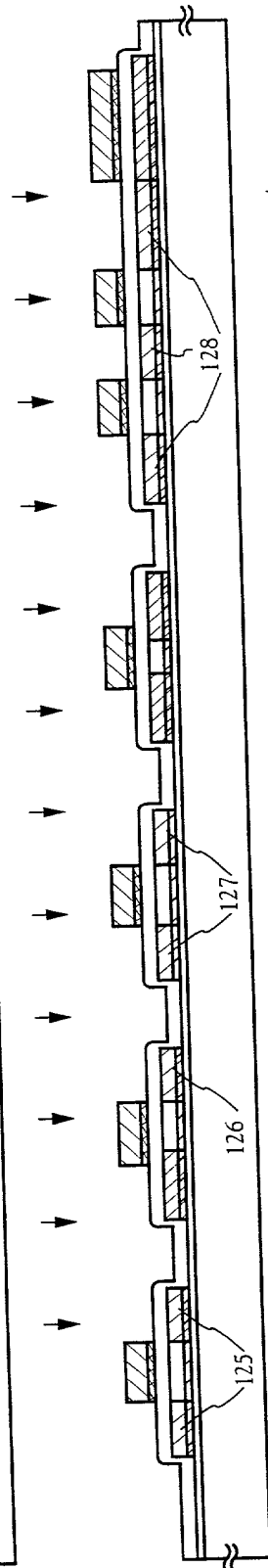


FIG. 3B

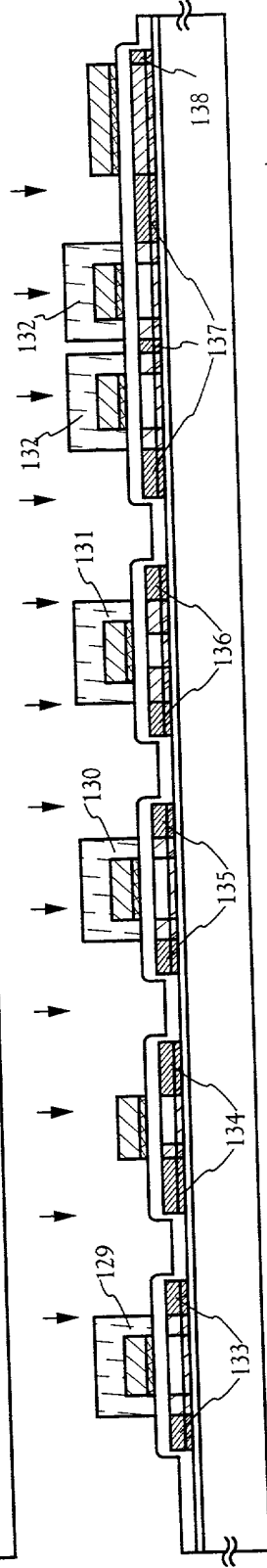


FIG. 3C

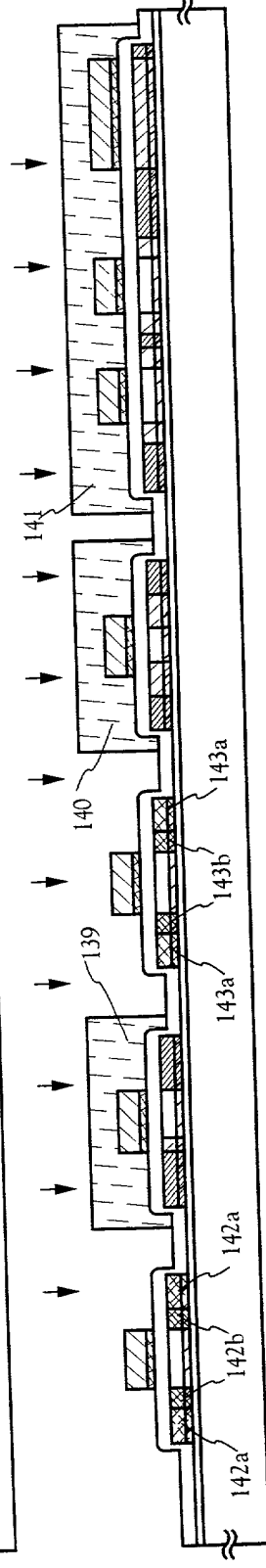


FIG. 3D

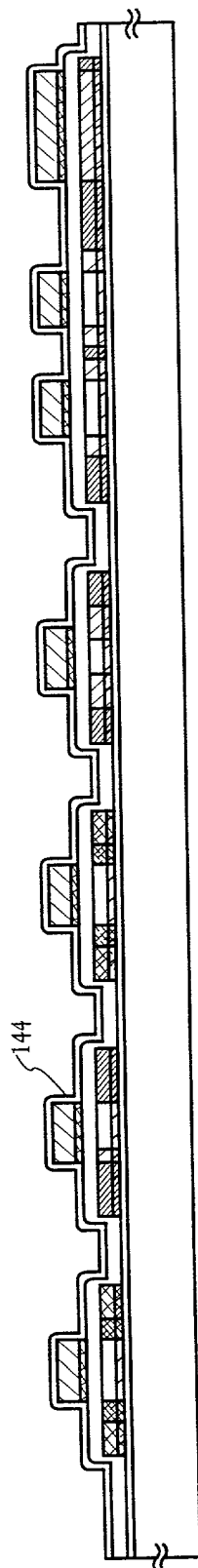


FIG. 4A

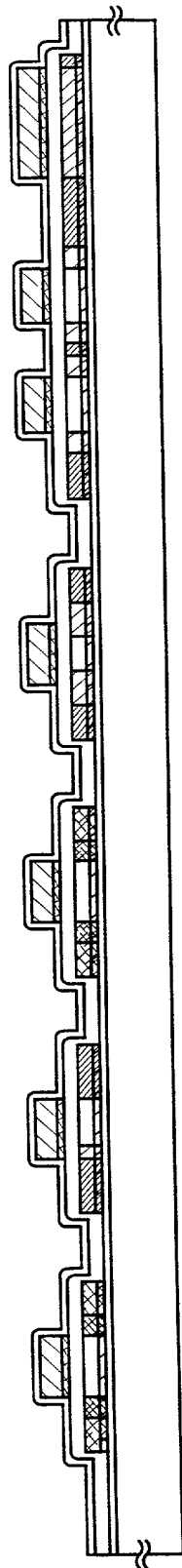


FIG. 4B

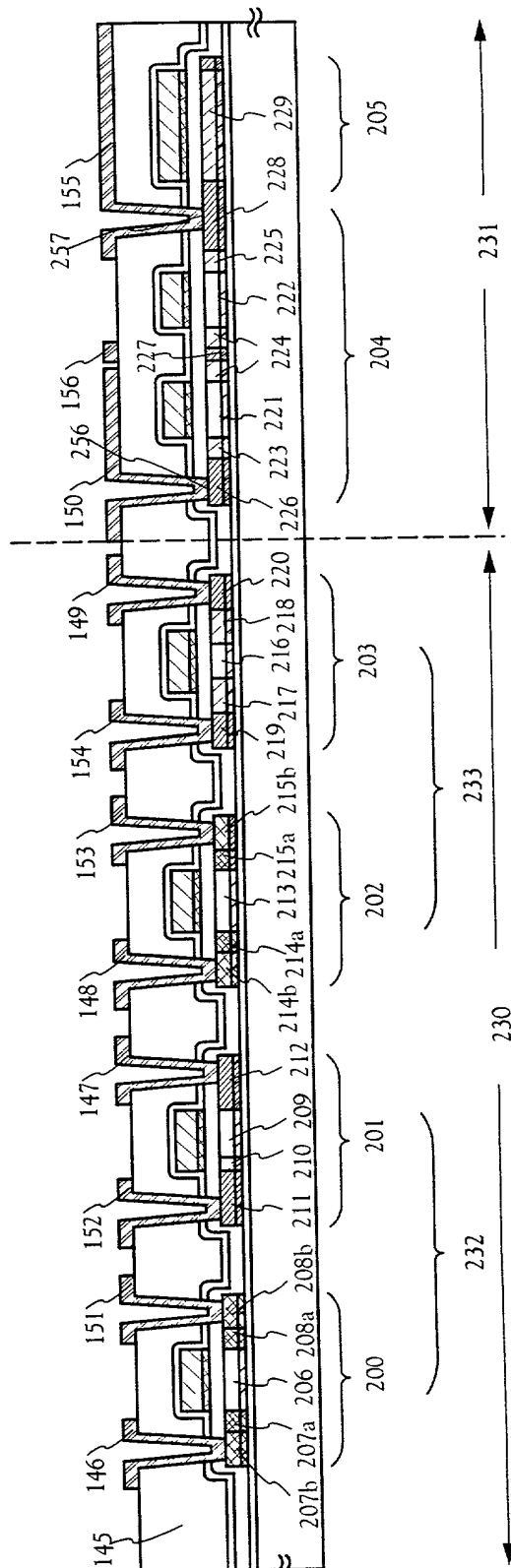


FIG. 4C

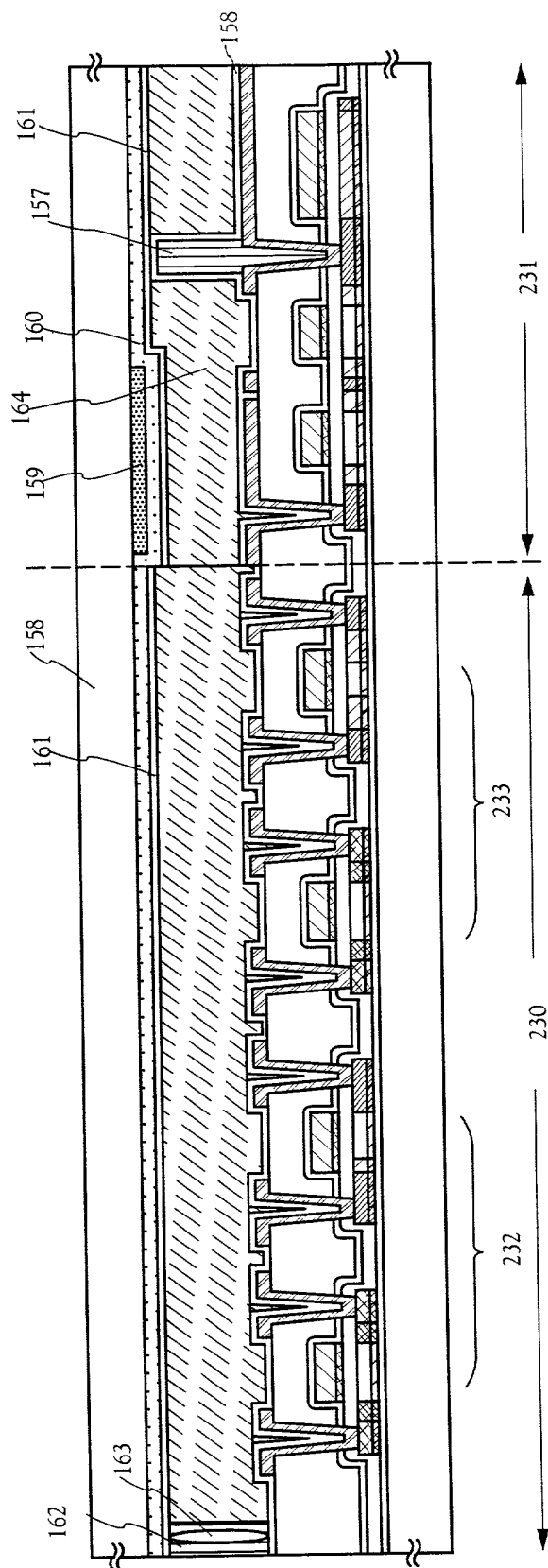


FIG. 5

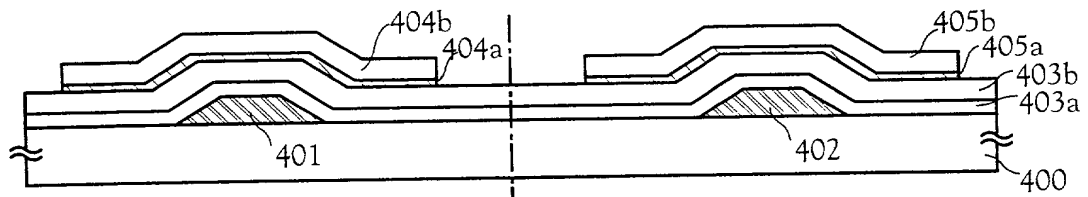


FIG. 6A

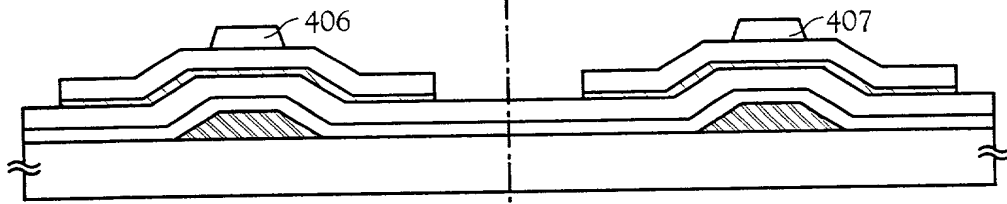


FIG. 6B

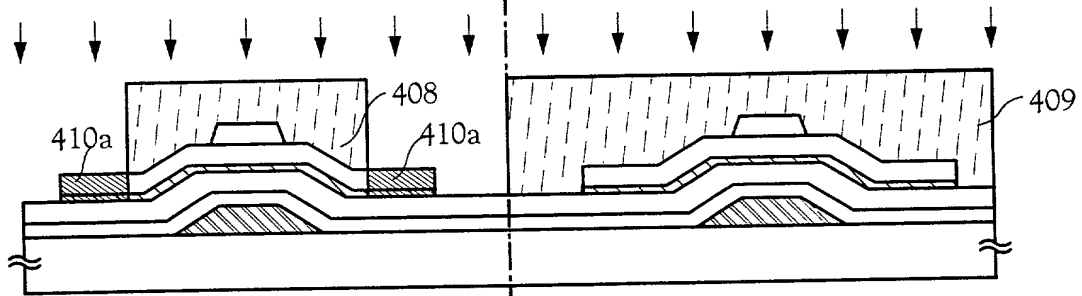


FIG. 6C

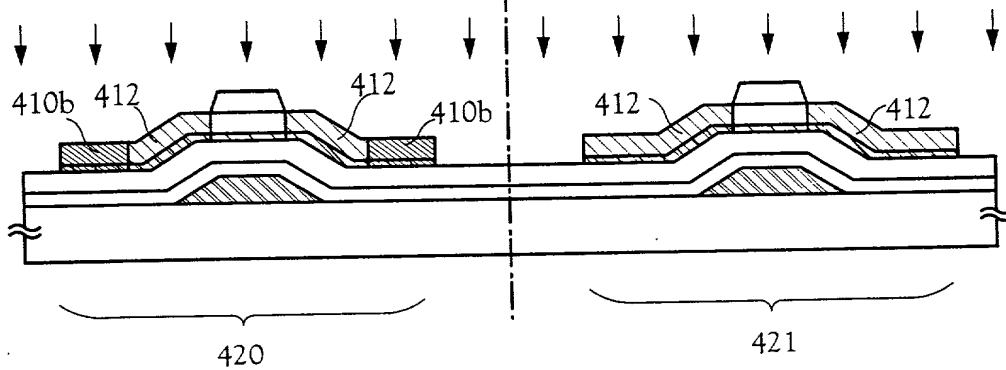


FIG. 6D

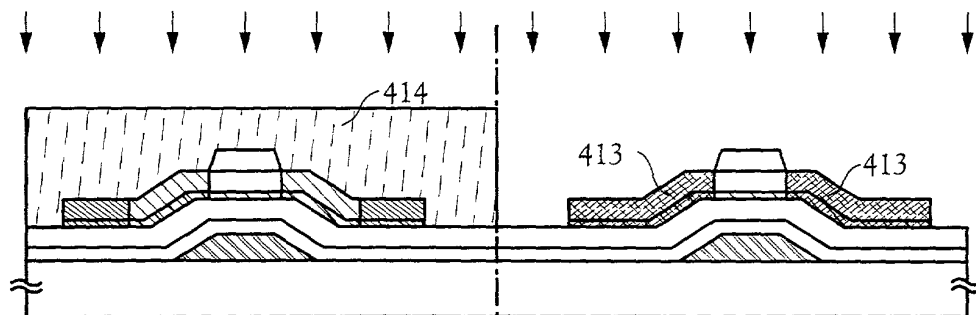


FIG. 7A

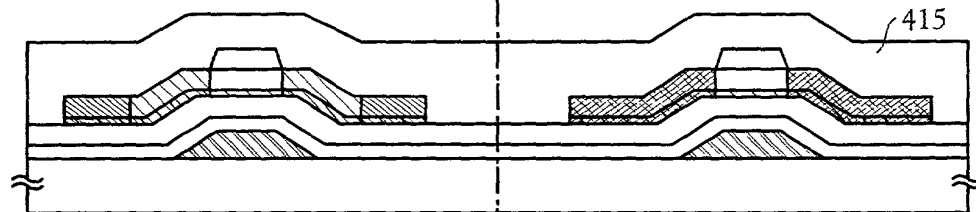


FIG. 7B

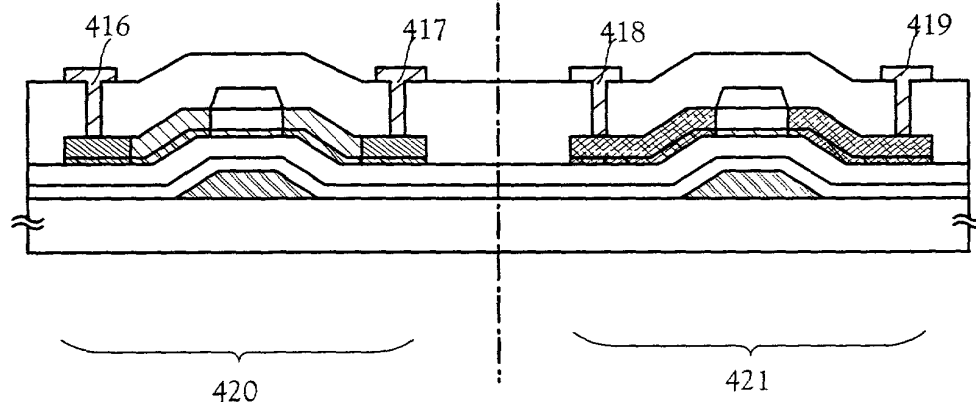


FIG. 7C

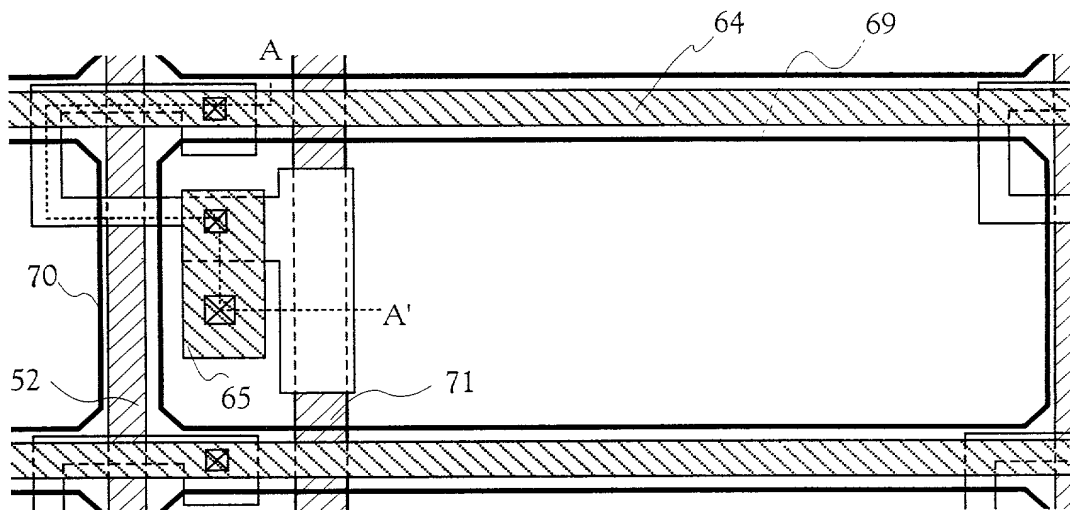


FIG. 8A

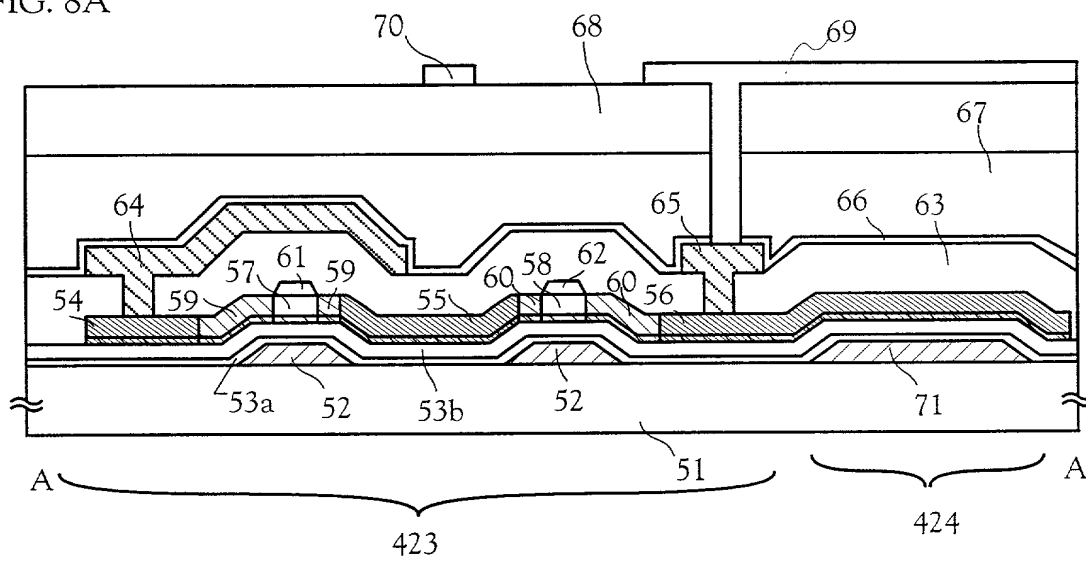


FIG. 8B

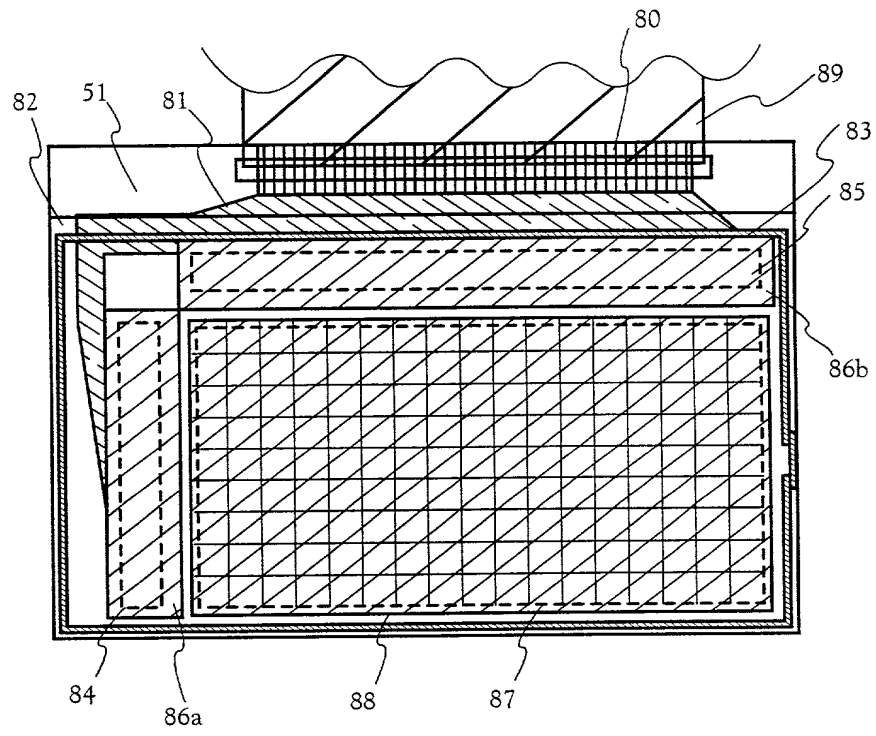


FIG. 9

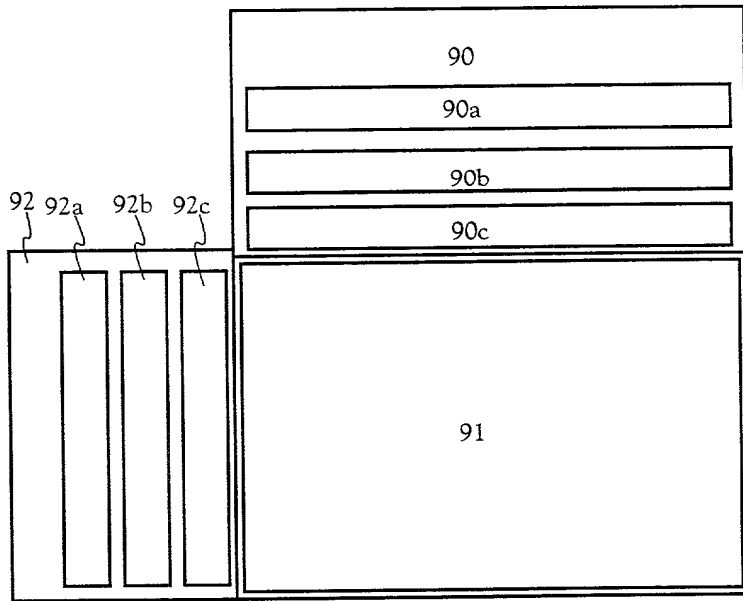


FIG. 10

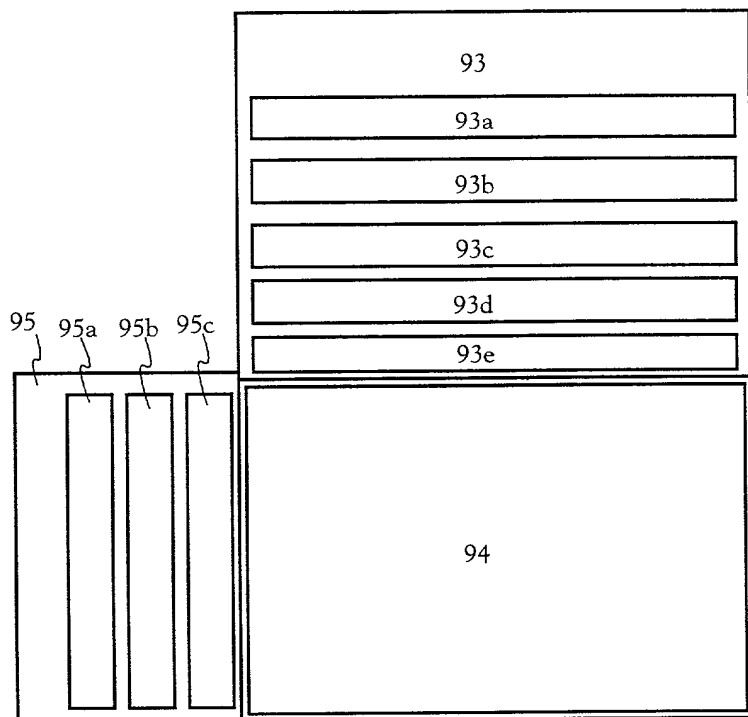


FIG. 11

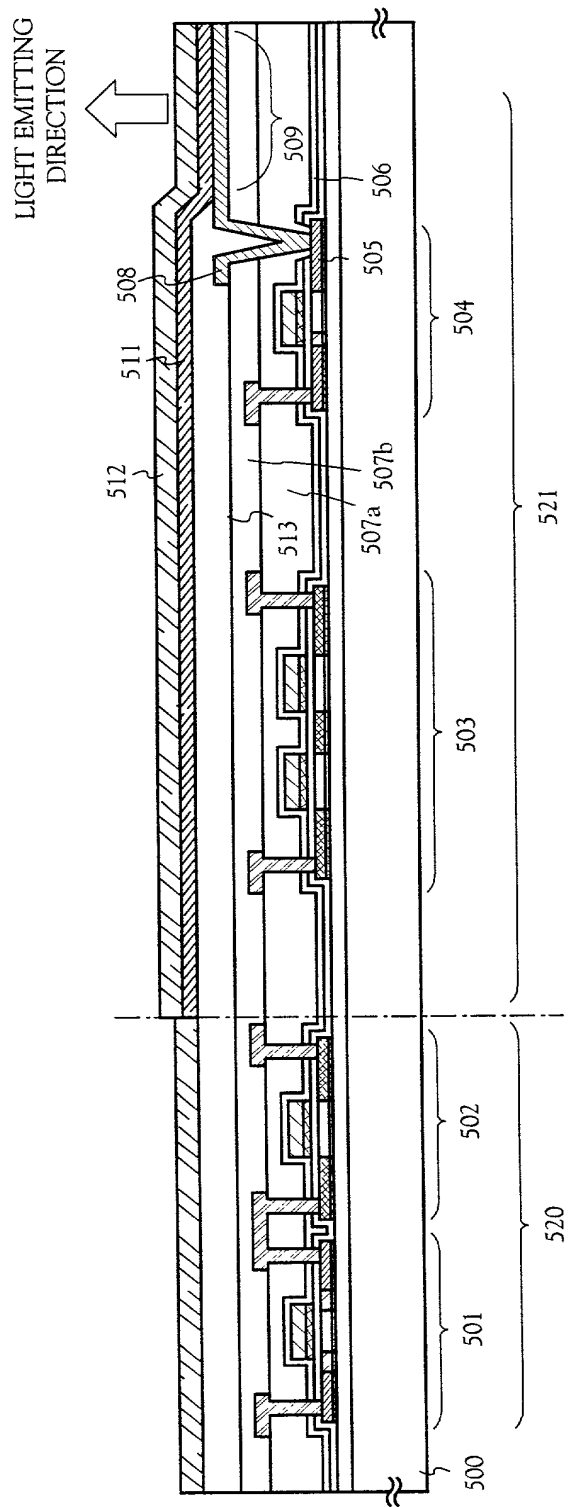


FIG. 12

FIG. 13A

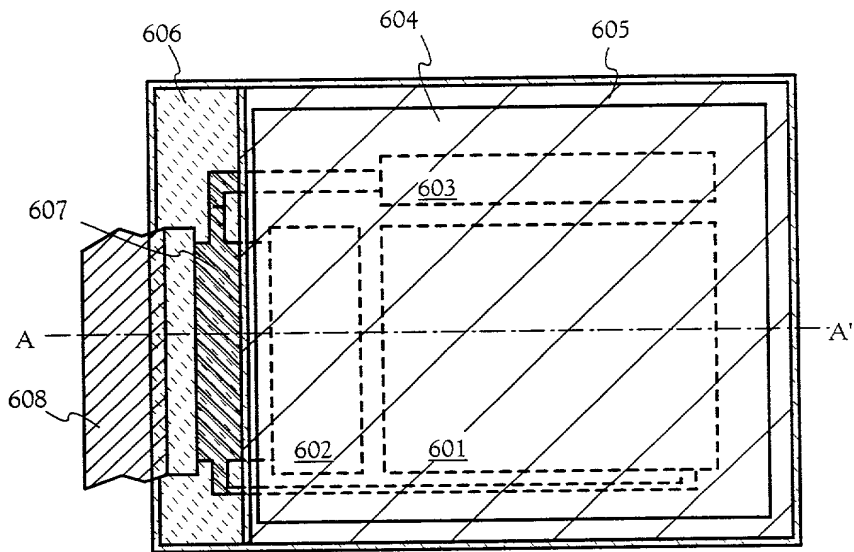


FIG. 13A

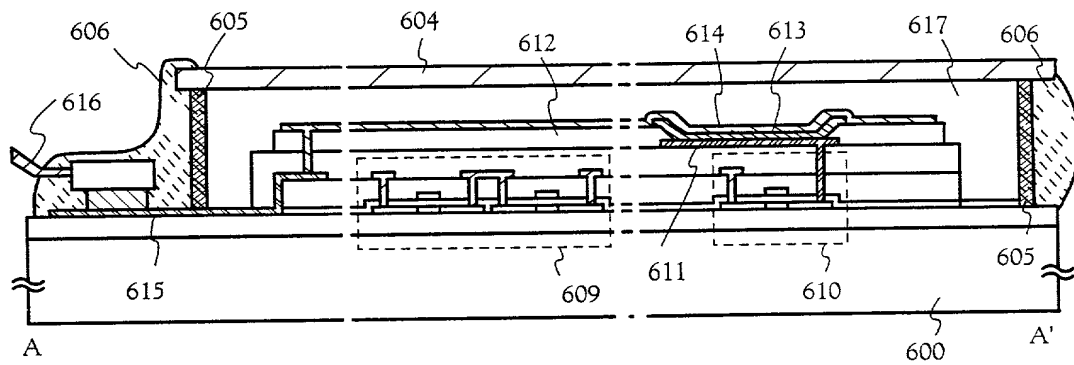


FIG. 13B

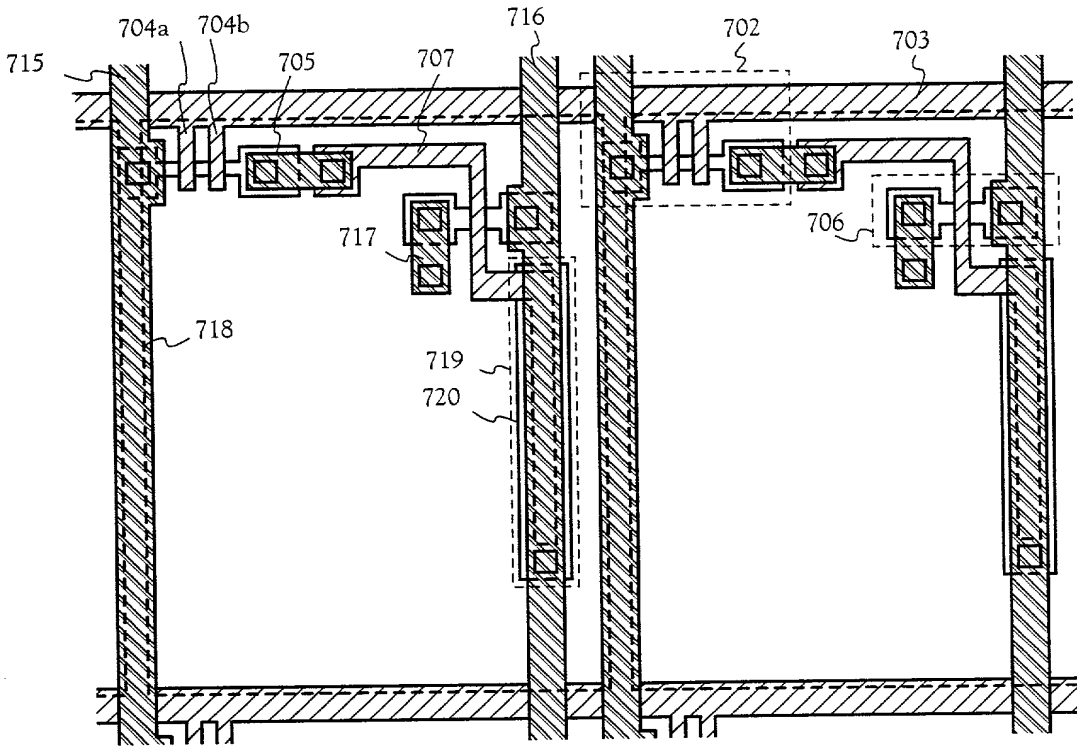


FIG. 14A

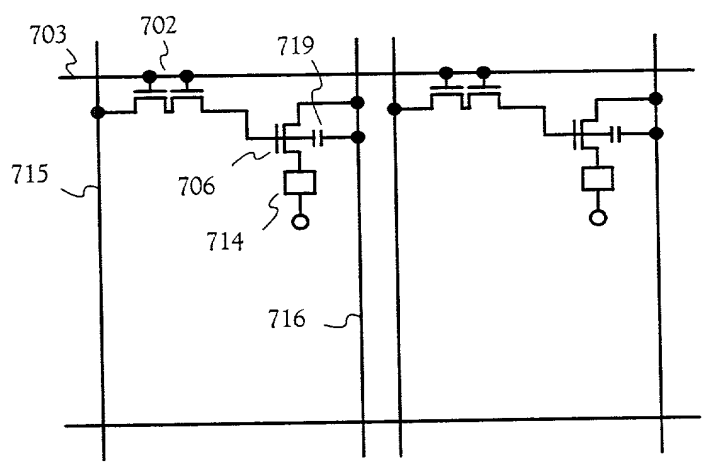


FIG. 14B

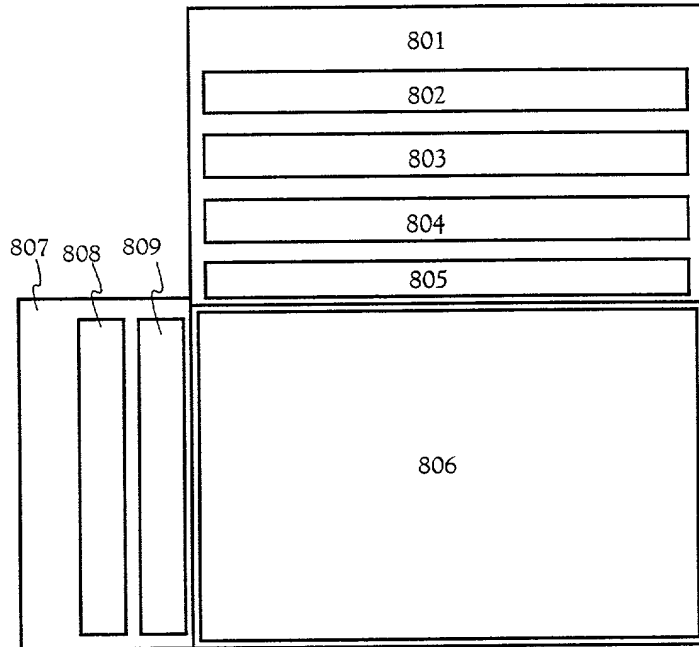


FIG. 15

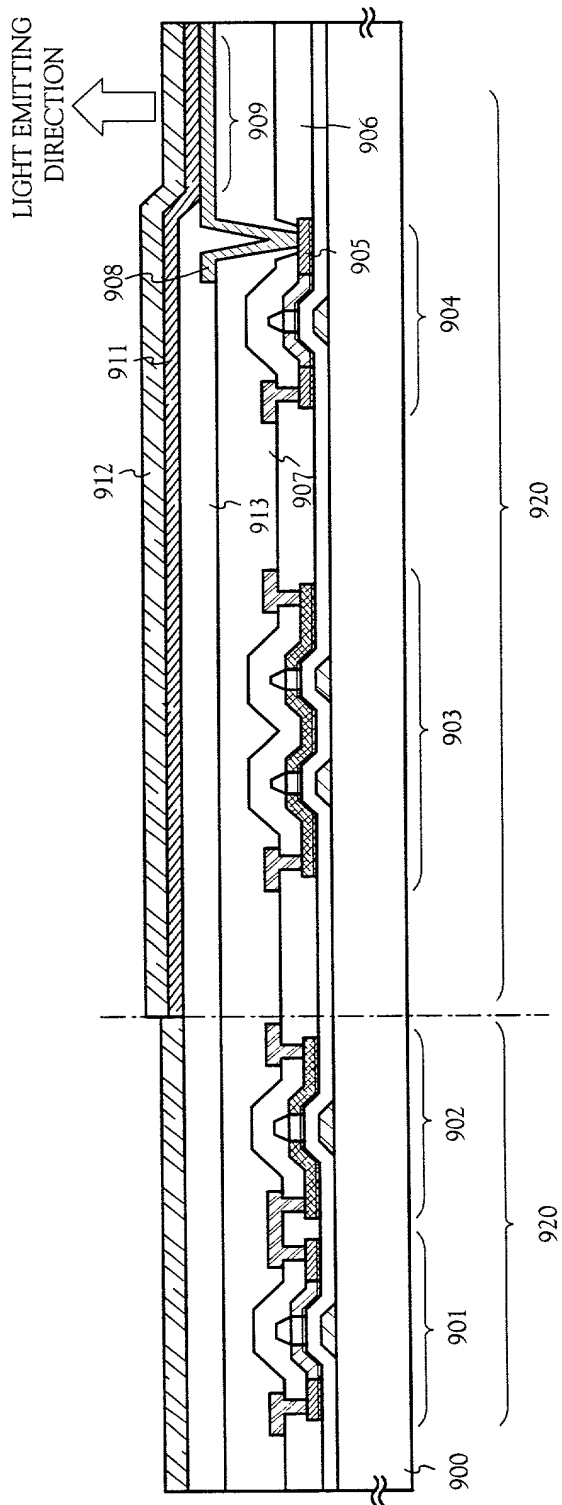


FIG. 16

The diagram illustrates a plasma processing apparatus 1000. At the top, a gas supply system 1006 is enclosed in a dashed box. It includes gas inlets for N₂ FOR LEAK, N₂O, N₂, SiH₄, GeH₄/H₂, NH₃, H₂, Ar, and NF₃. Each inlet is equipped with a valve (1012) and a check valve (1013). The gas lines converge into a single line that enters the main chamber 1001. The main chamber 1001 contains a substrate 1003 mounted on a stage 1002. A pump 1005 is connected to the chamber to maintain vacuum. A power supply 1004 is connected to the stage 1002. A control system 1007, shown in a dashed box at the bottom, includes a controller 1008, a valve driver 1009, and a power supply 1010. A legend box 1011 defines the symbols: a triangle for a valve (1012), a rectangle with an 'X' for a check valve (1013), and a rectangle with 'N₂' for a gas inlet (1014).

FIG. 17

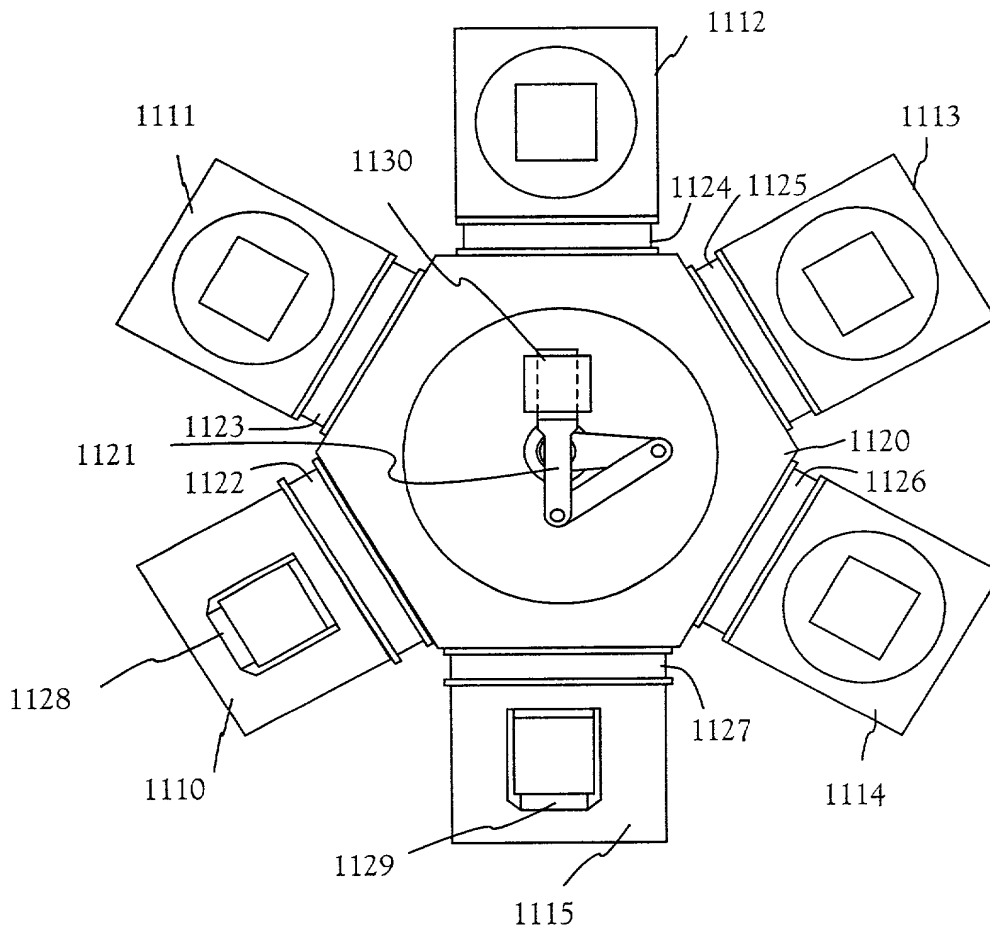


FIG. 18

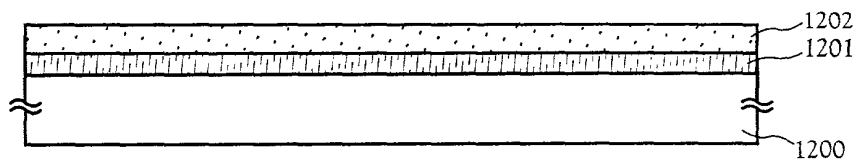


FIG. 19A

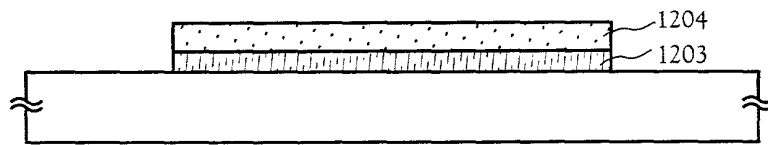


FIG. 19B

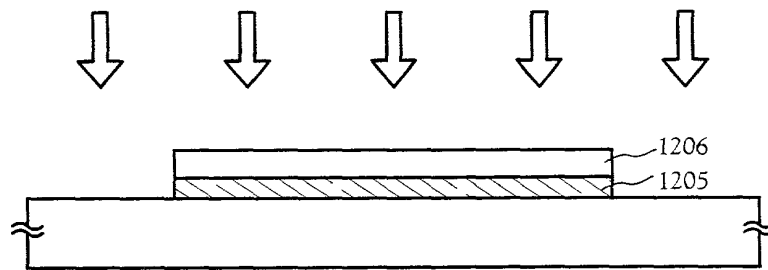


FIG. 19C

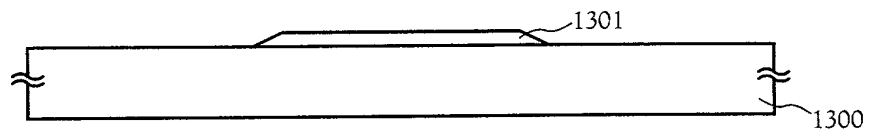


FIG. 20A

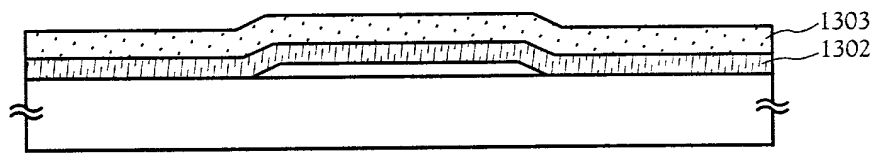


FIG. 20B

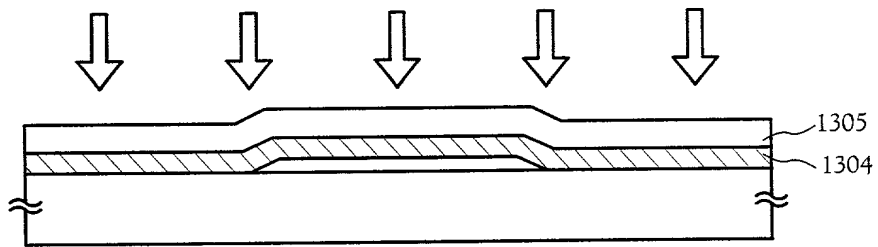


FIG. 20C

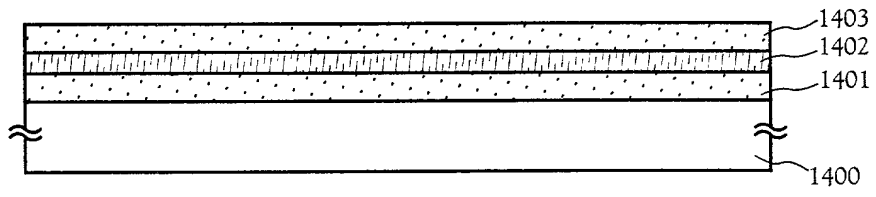


FIG. 21A

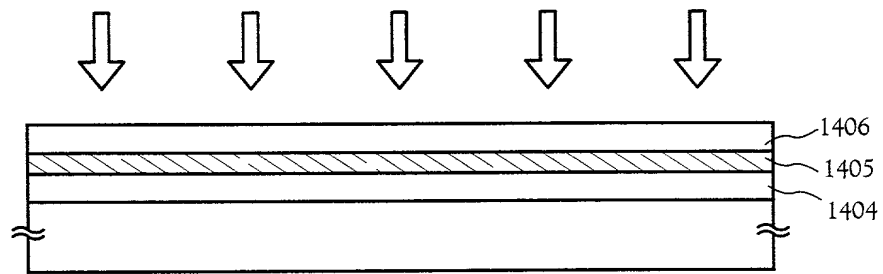


FIG. 21B

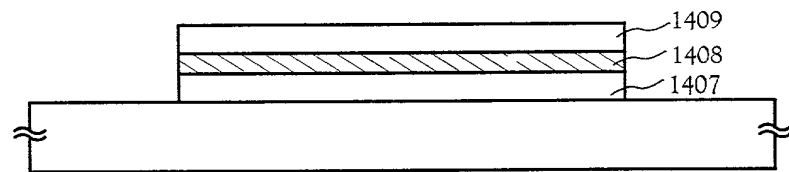


FIG. 21C

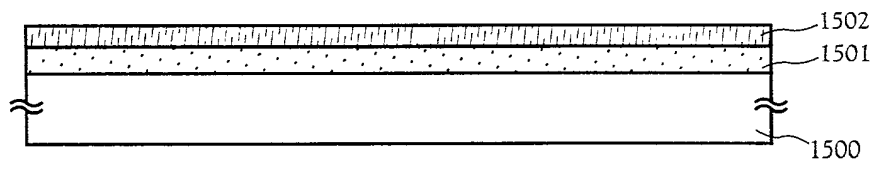


FIG. 22A

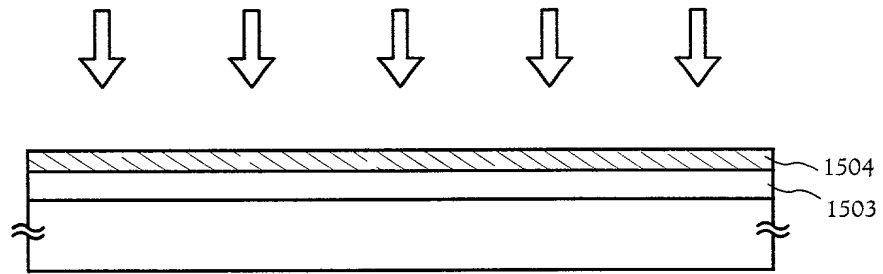


FIG. 22B

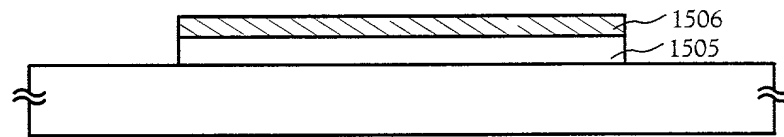


FIG. 22C

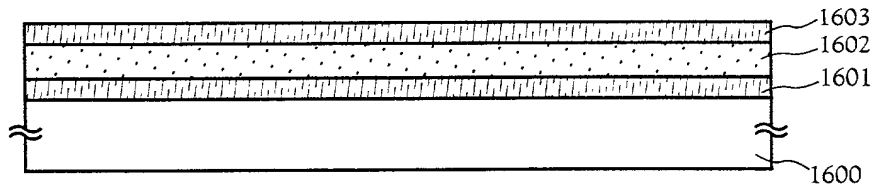


FIG. 23A

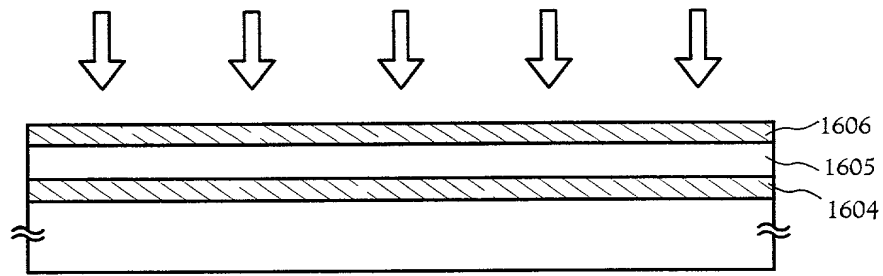


FIG. 23B

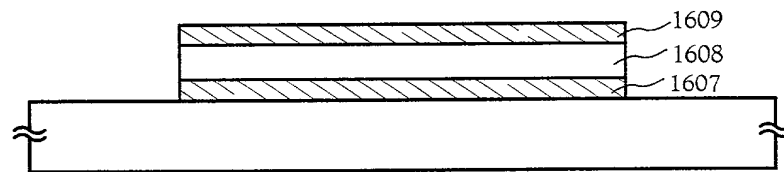


FIG. 23C

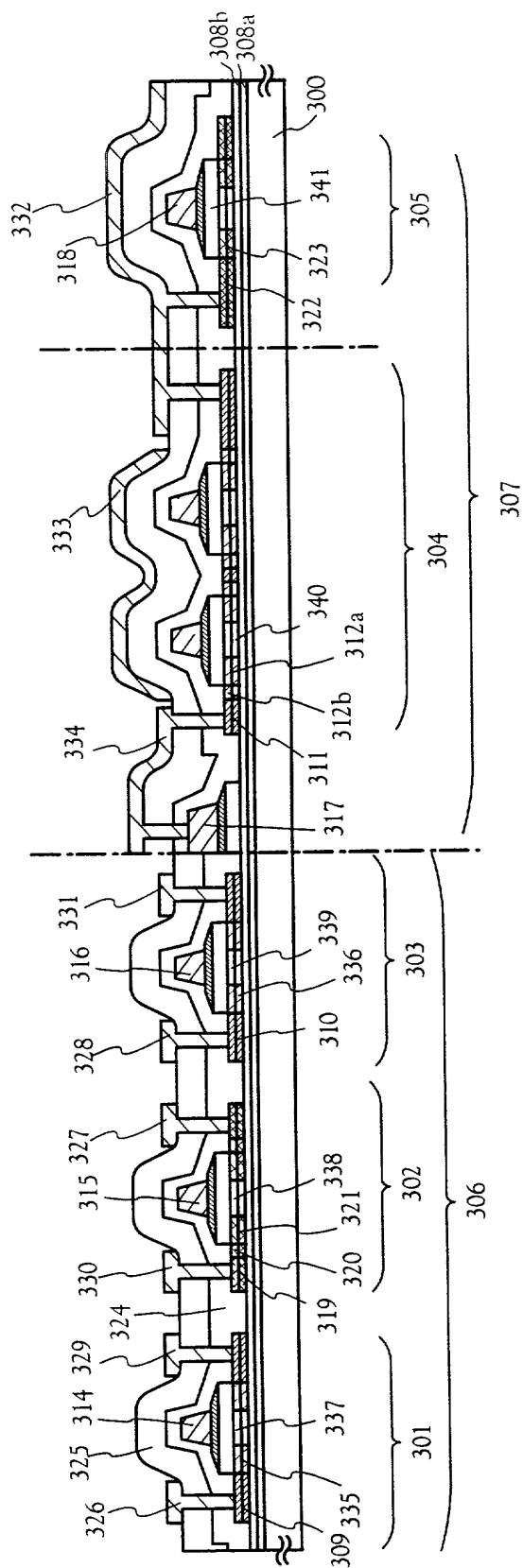


FIG. 24

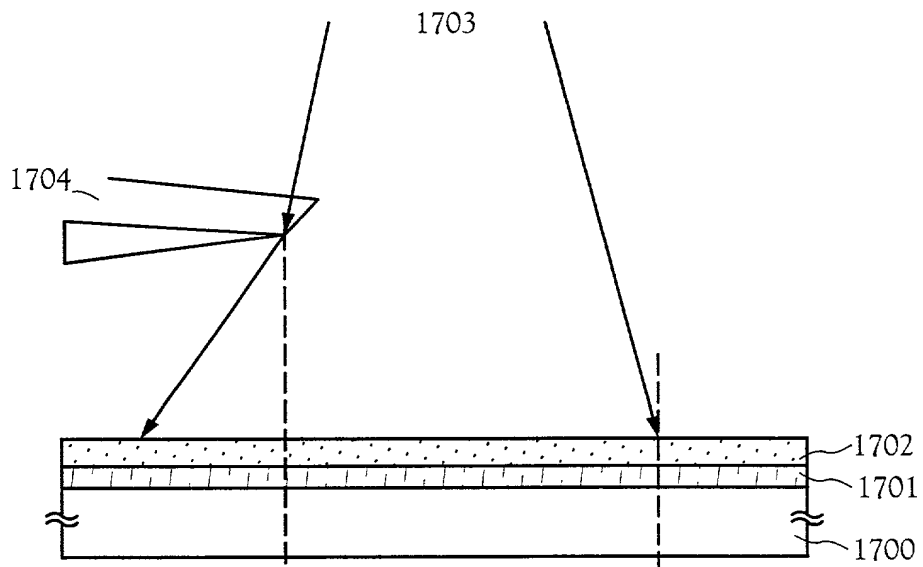


FIG. 25A

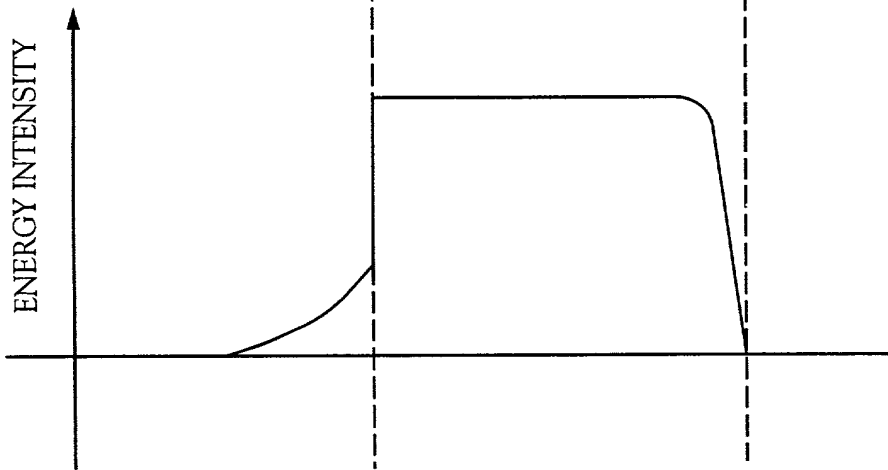


FIG. 25B

FIG. 26A

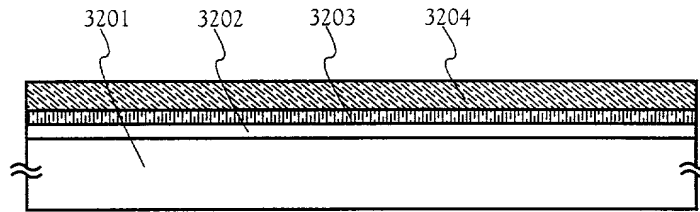


FIG. 26B

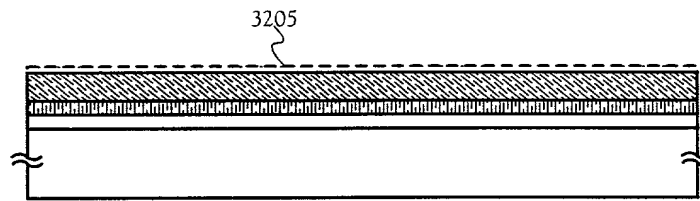


FIG. 26C

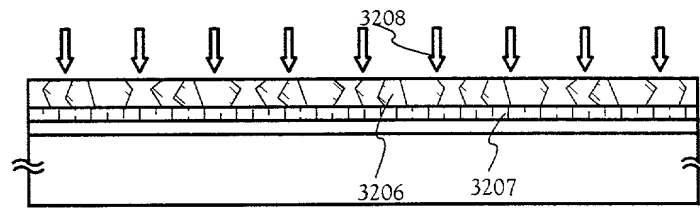
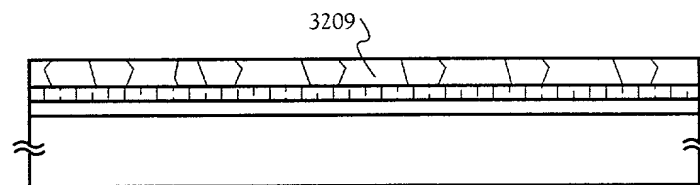
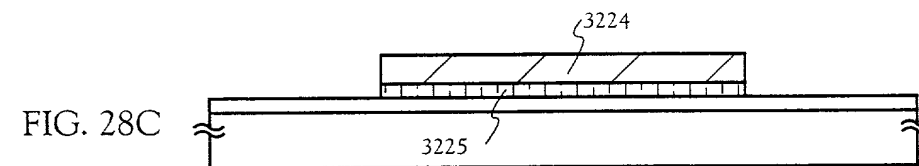
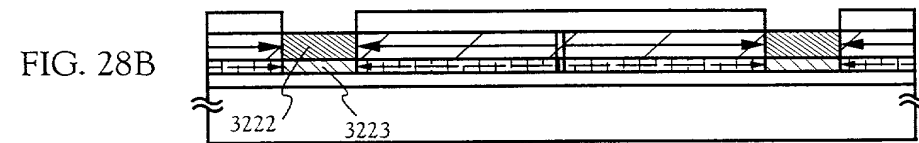
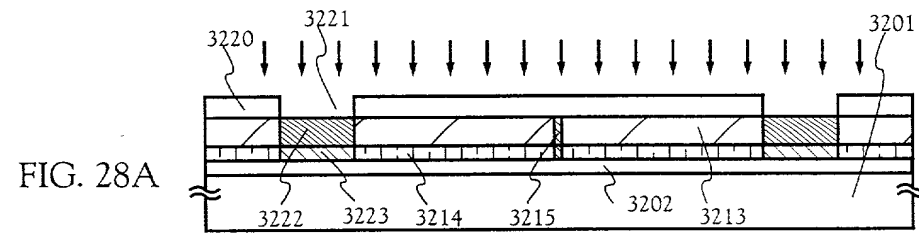
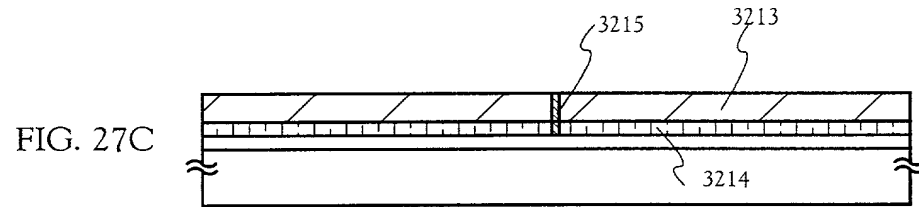
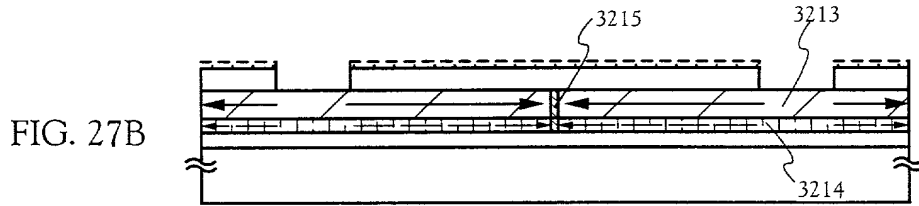
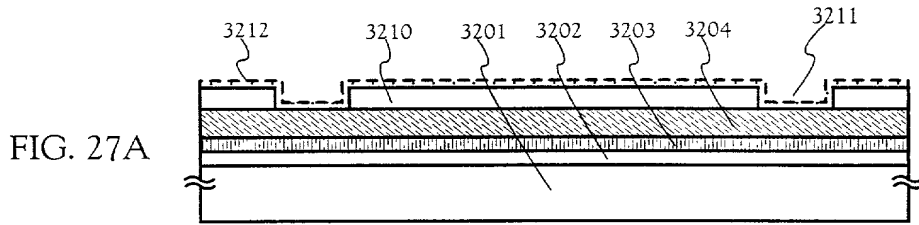
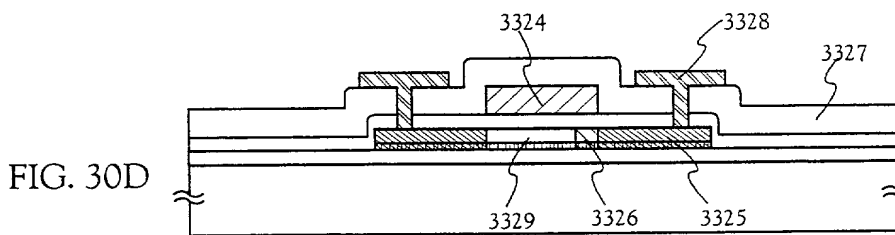
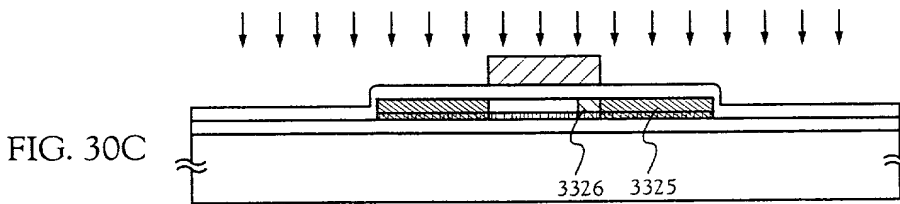
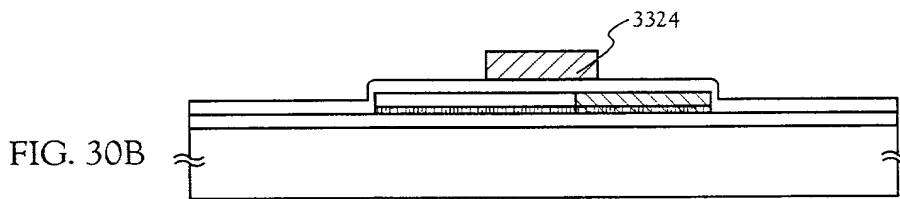
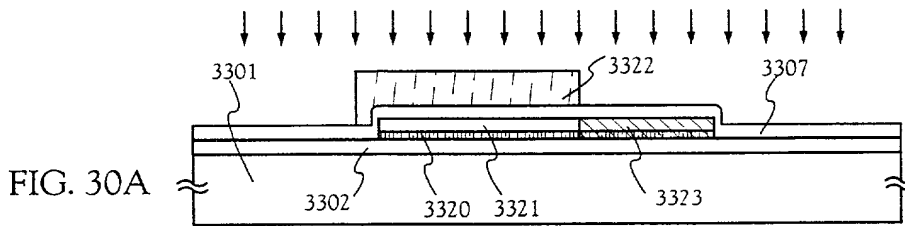
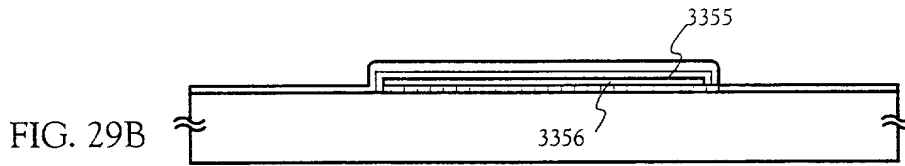
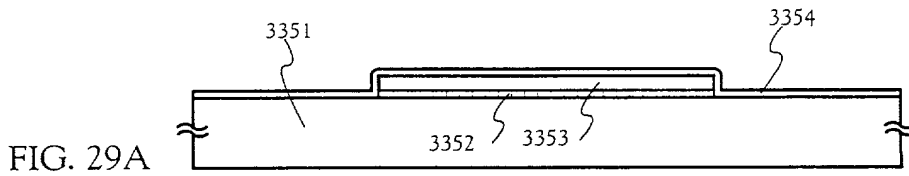
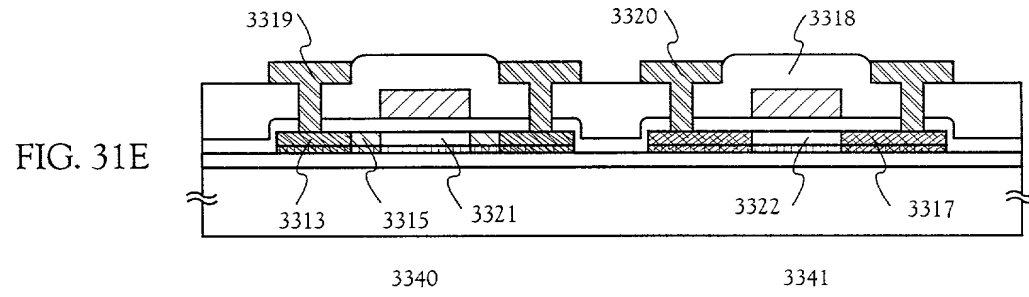
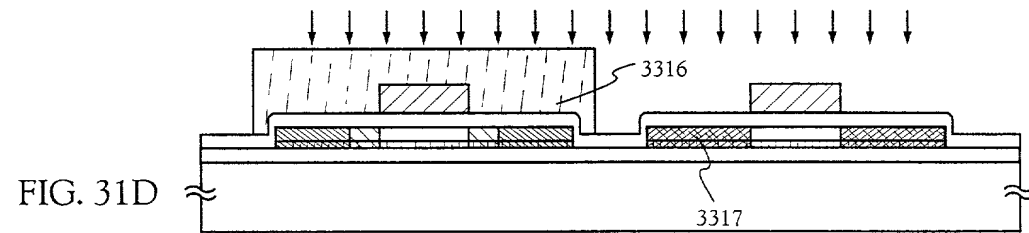
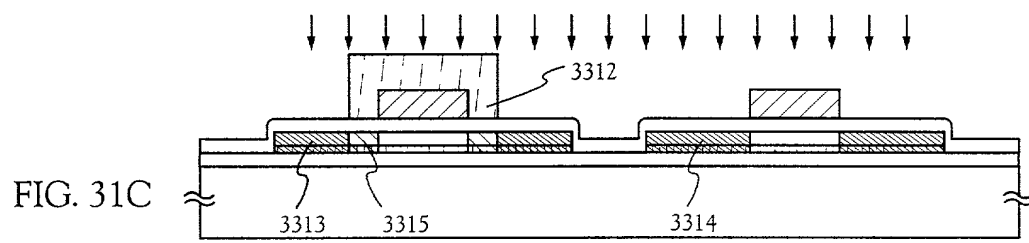
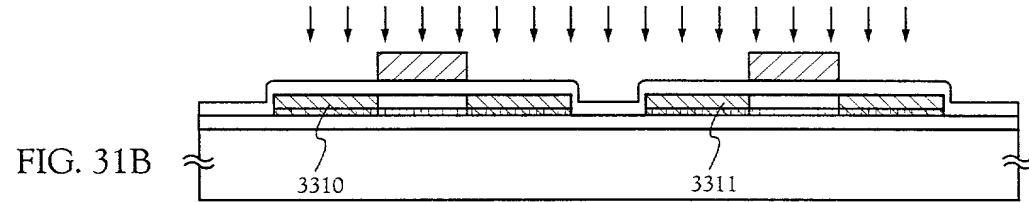
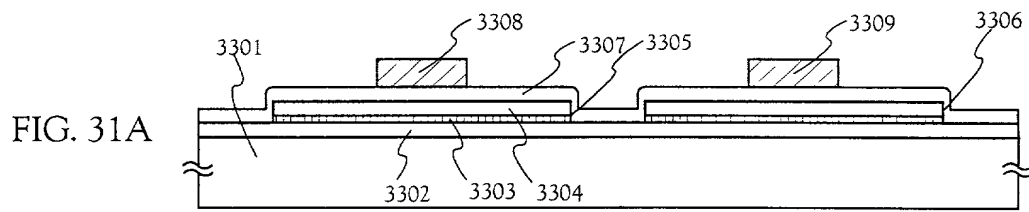


FIG. 26D









3340

3341

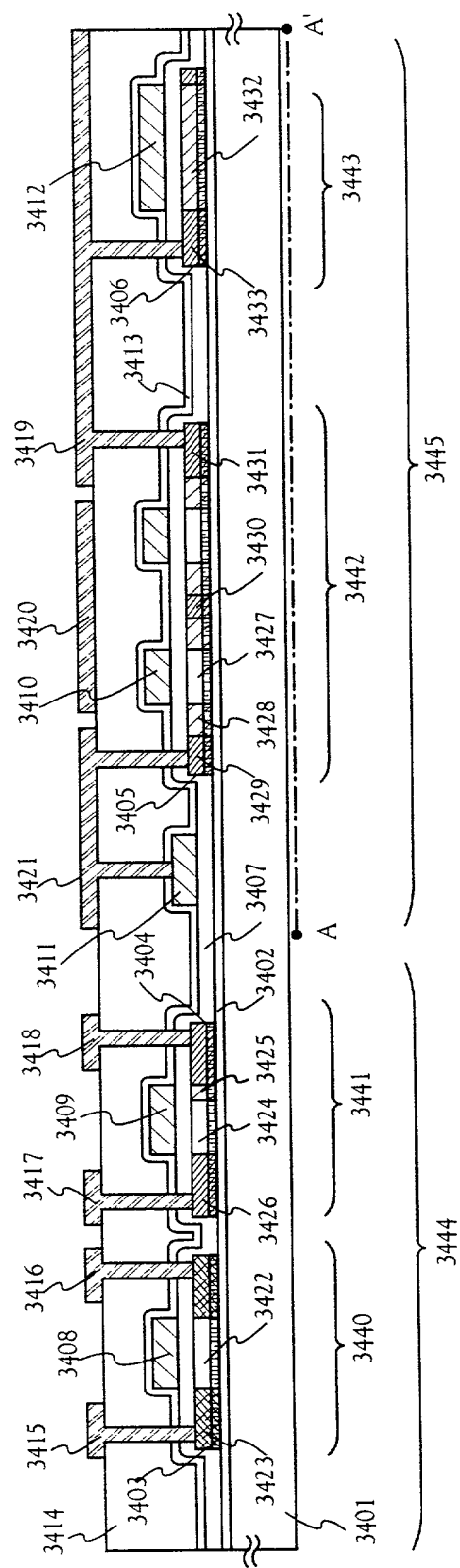


FIG. 32

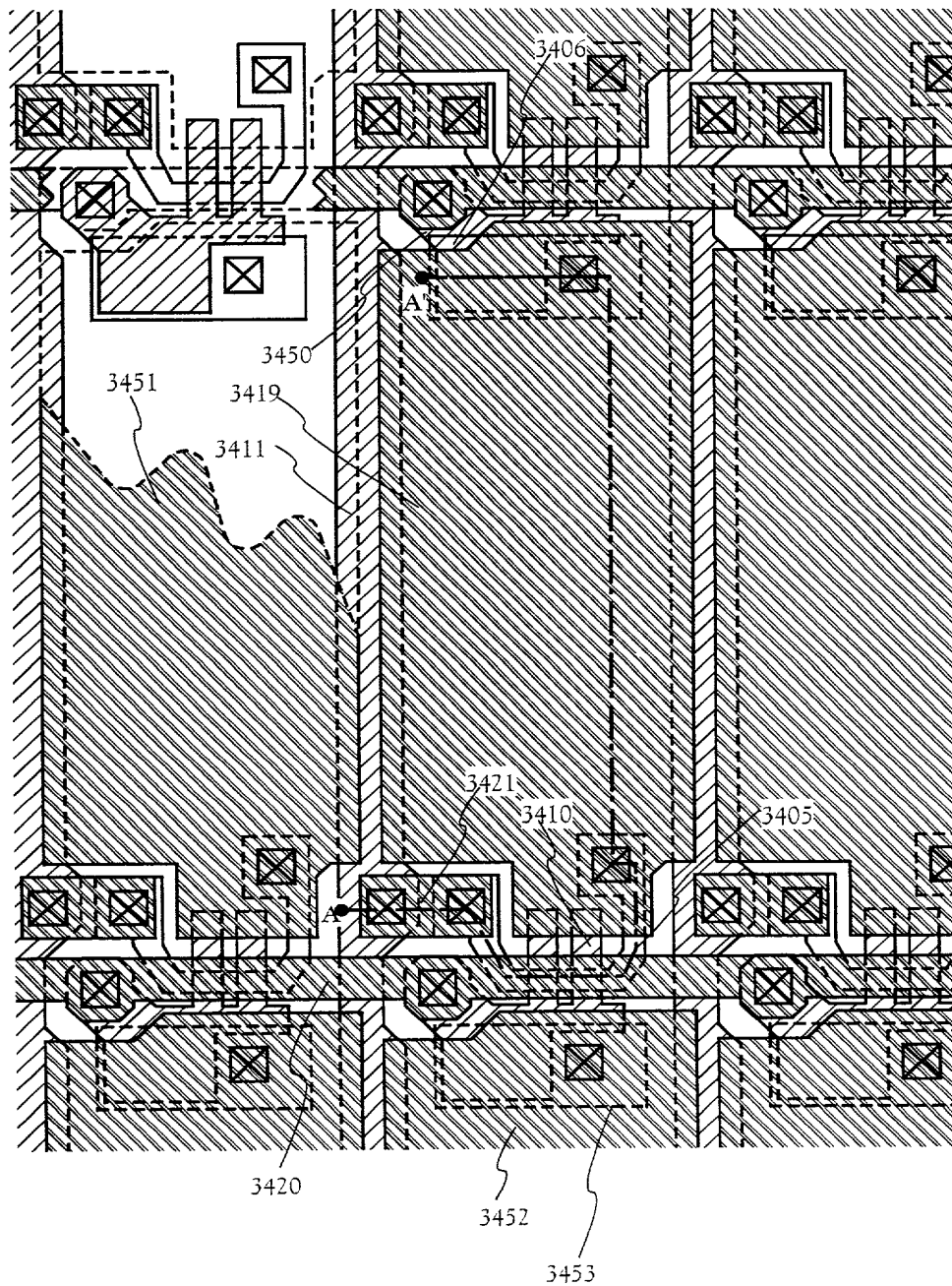


FIG. 33

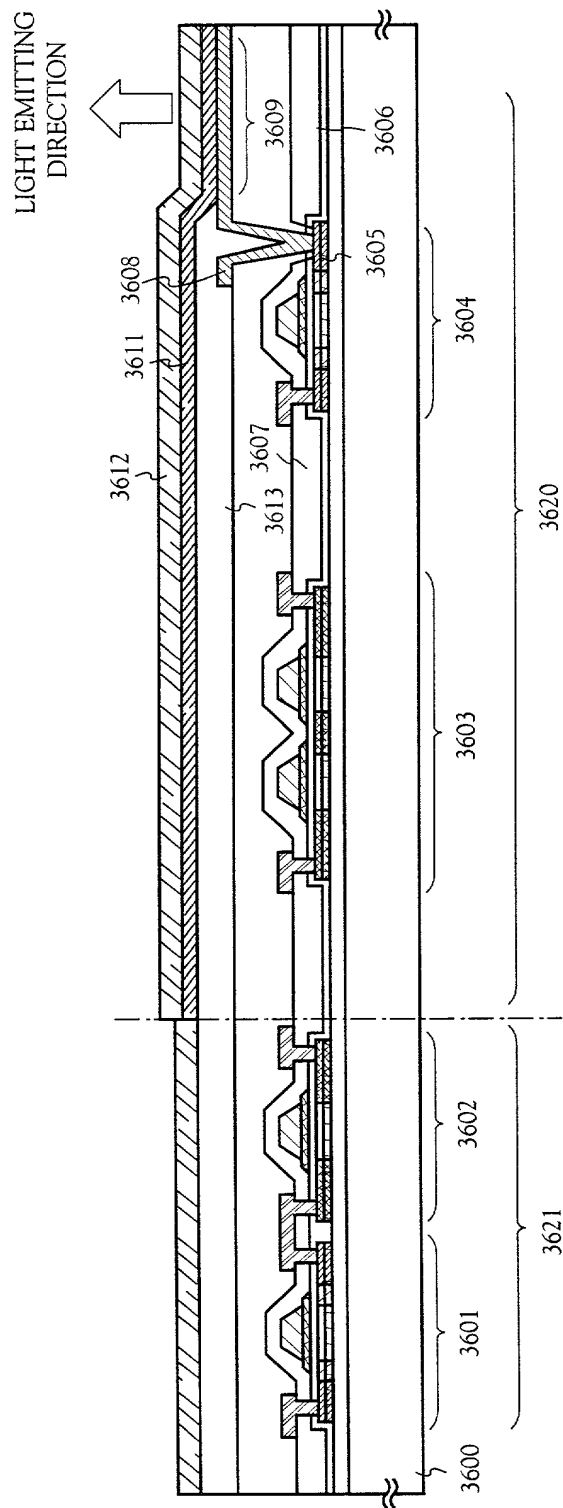


FIG. 34

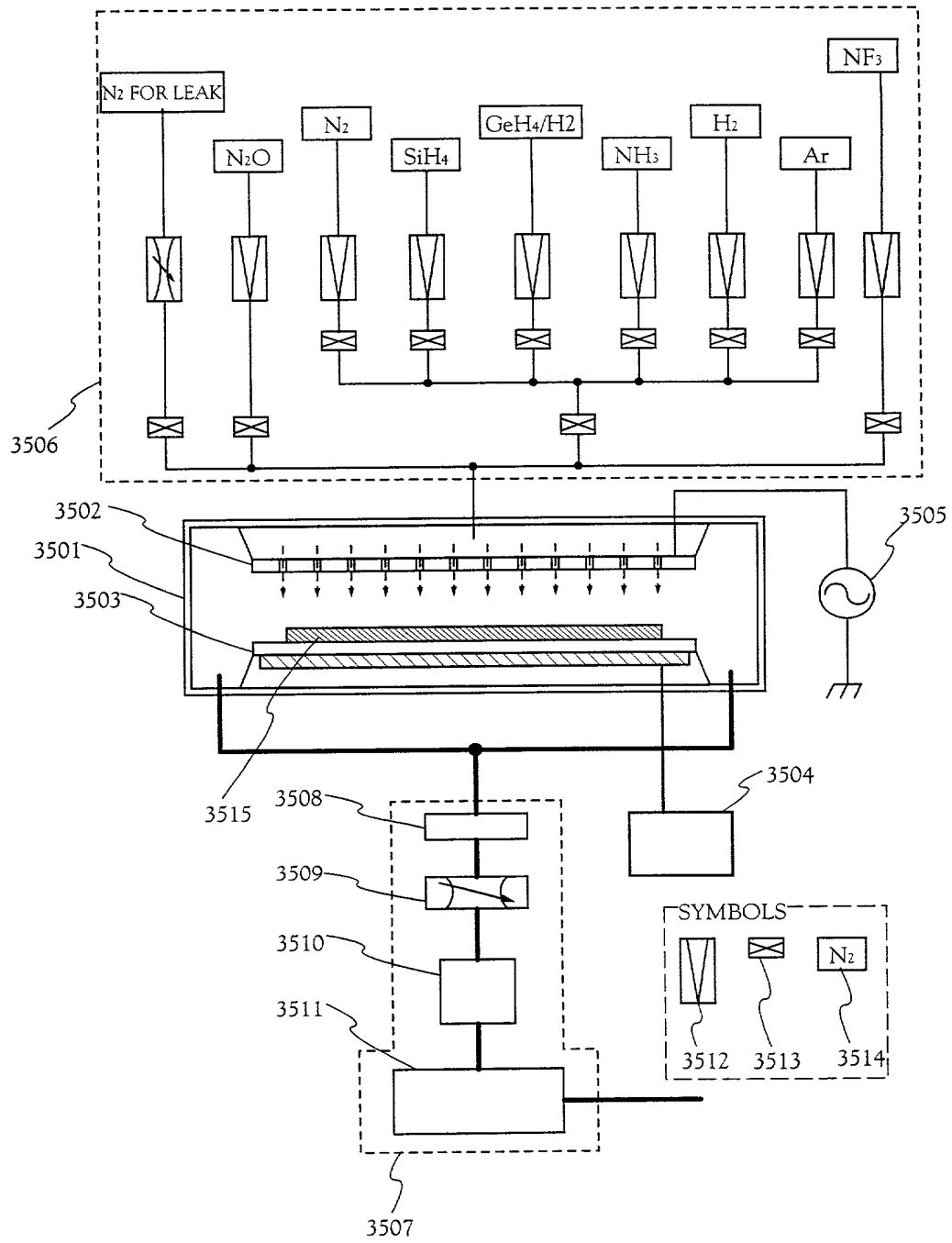


FIG. 35

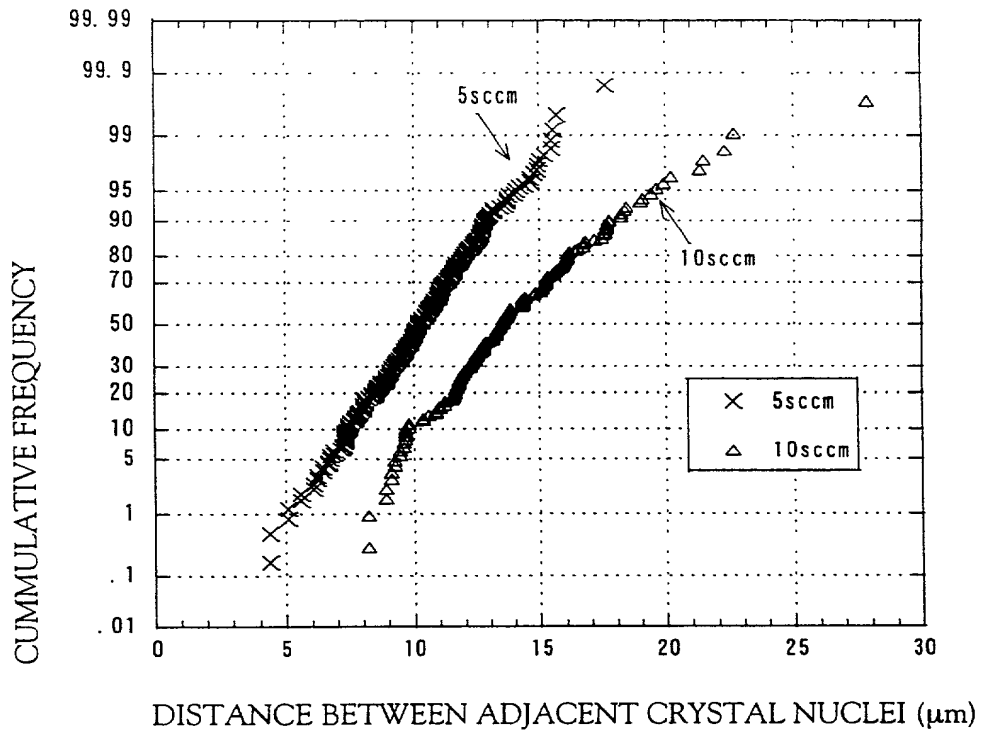


FIG. 36A

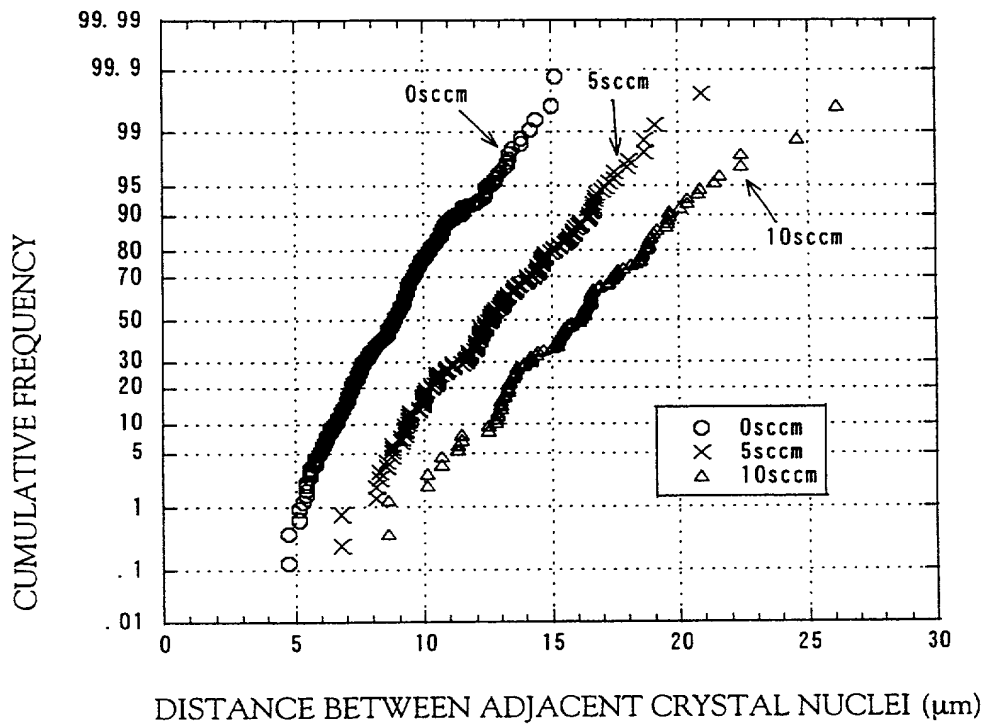


FIG. 36B

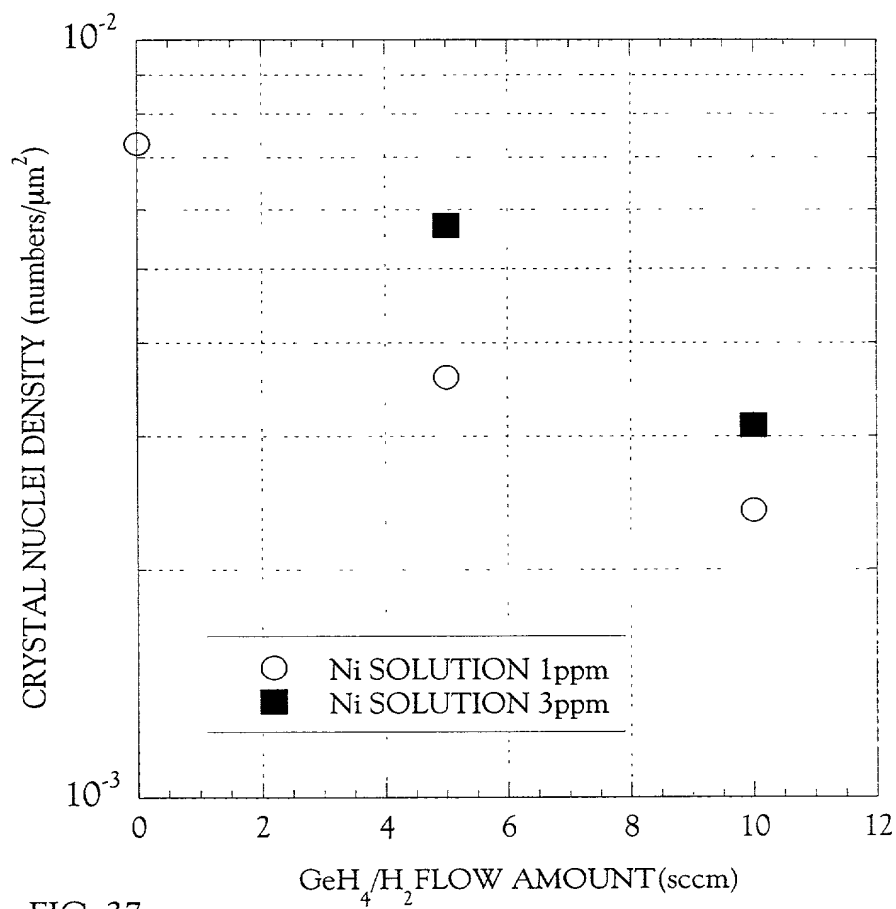


FIG. 37

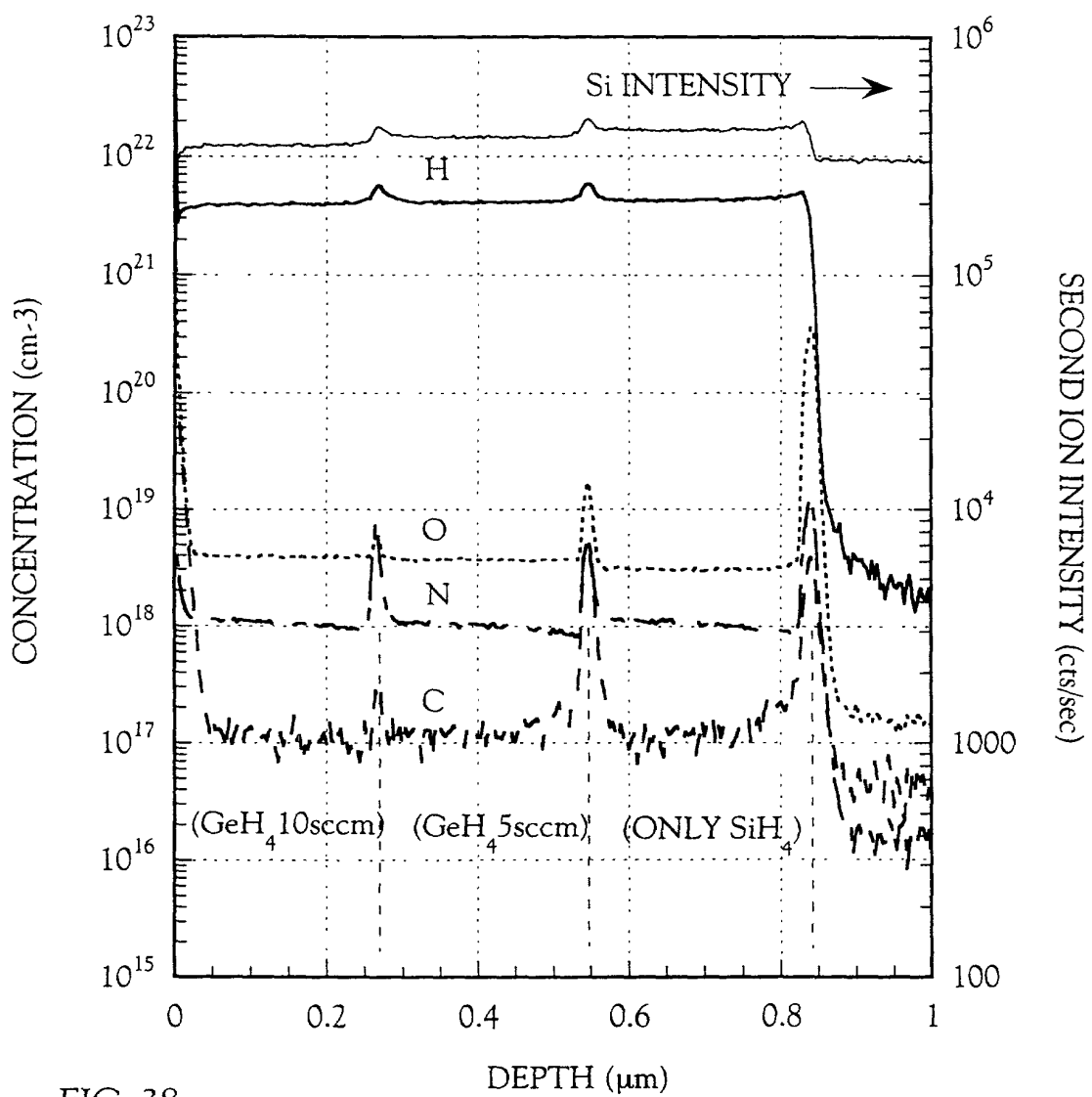


FIG. 38

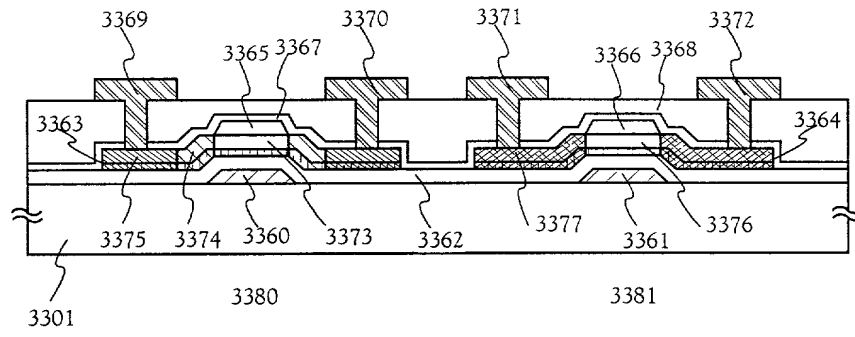


FIG. 39

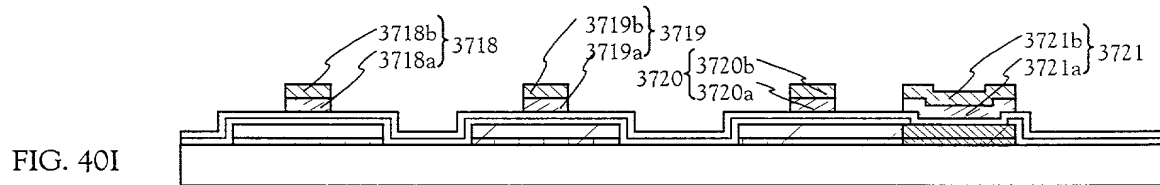
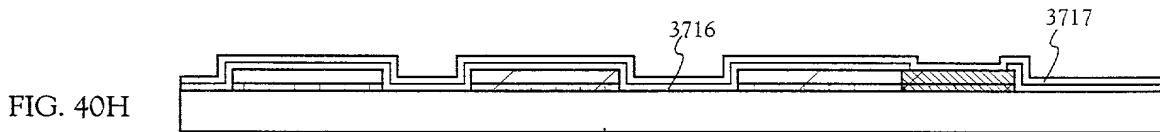
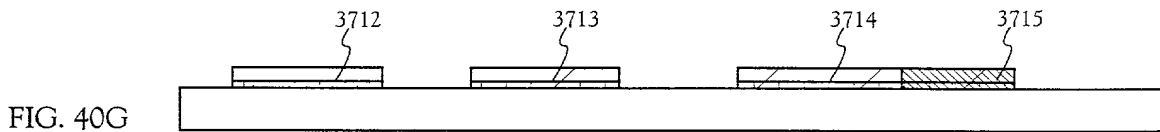
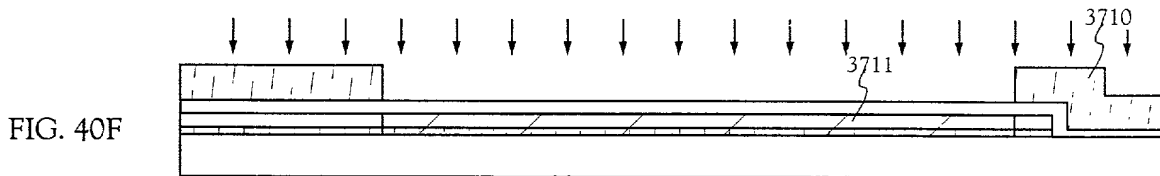
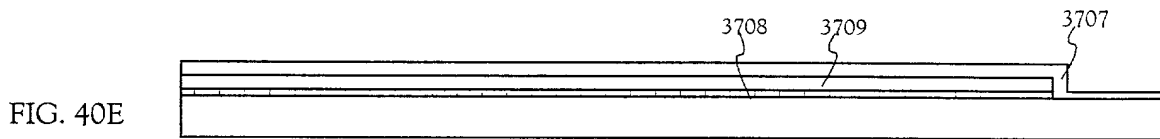
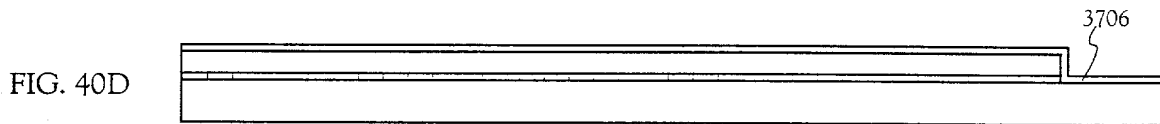
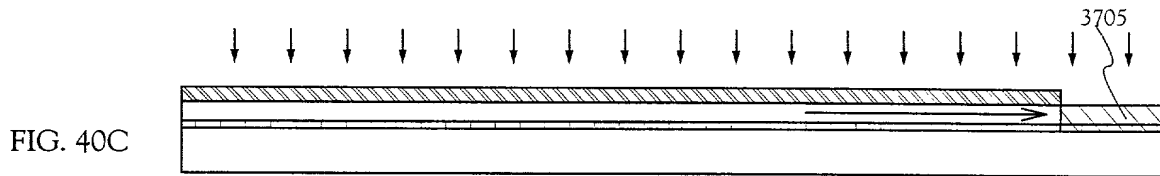
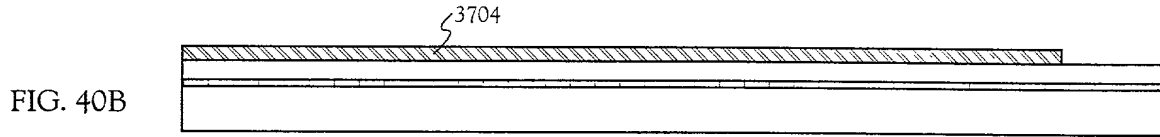
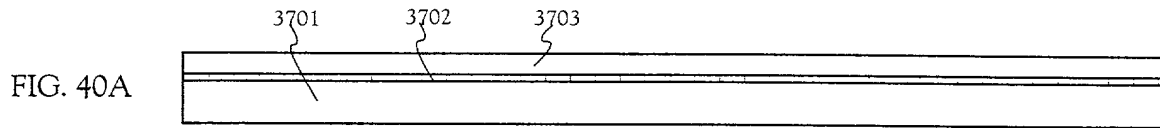


FIG. 41A

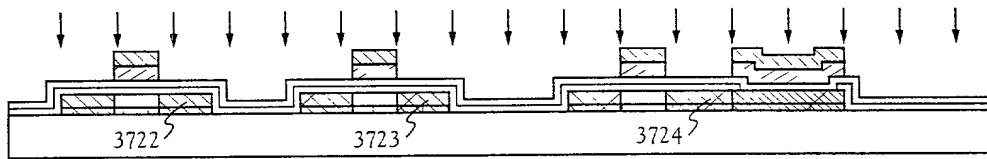


FIG. 41B

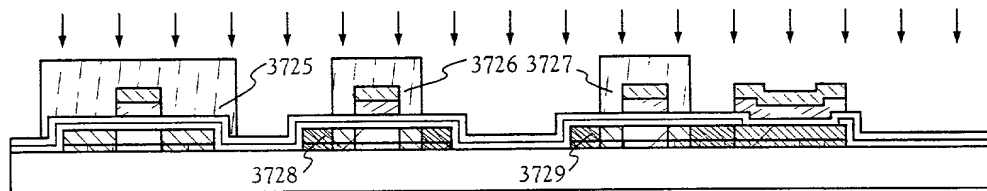


FIG. 41C

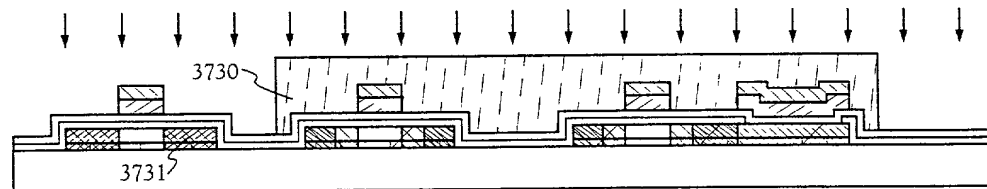


FIG. 41D

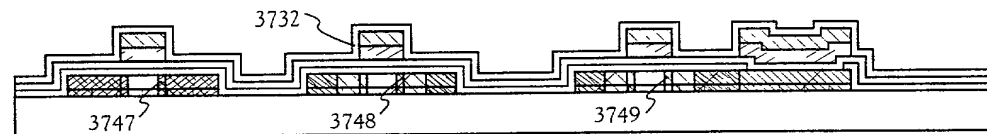


FIG. 41E

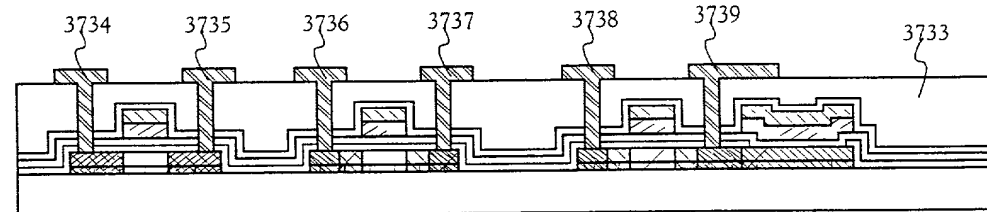
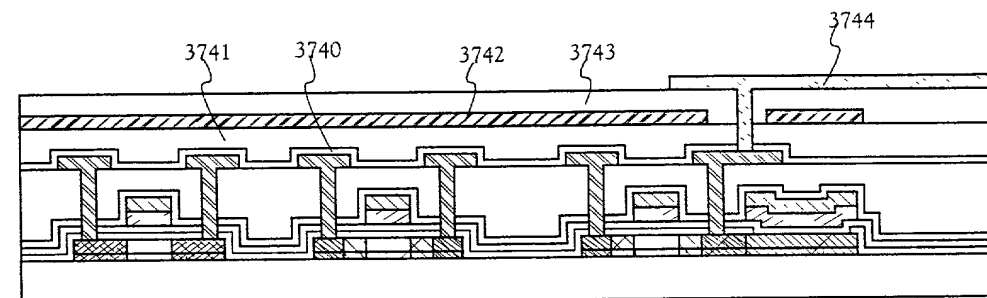


FIG. 41F



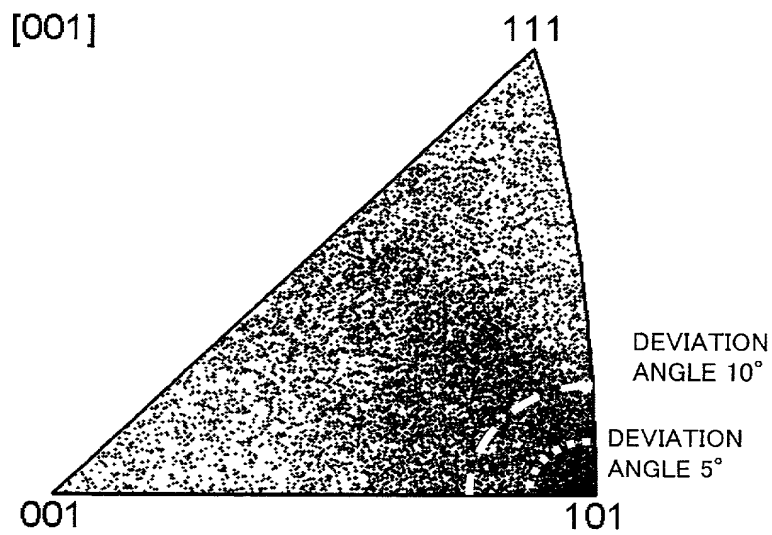


FIG. 42A

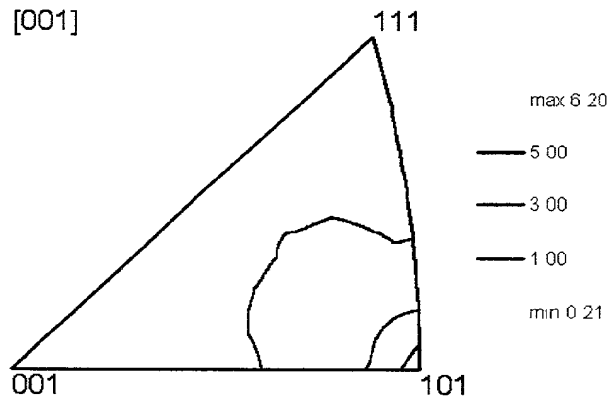


FIG. 42B

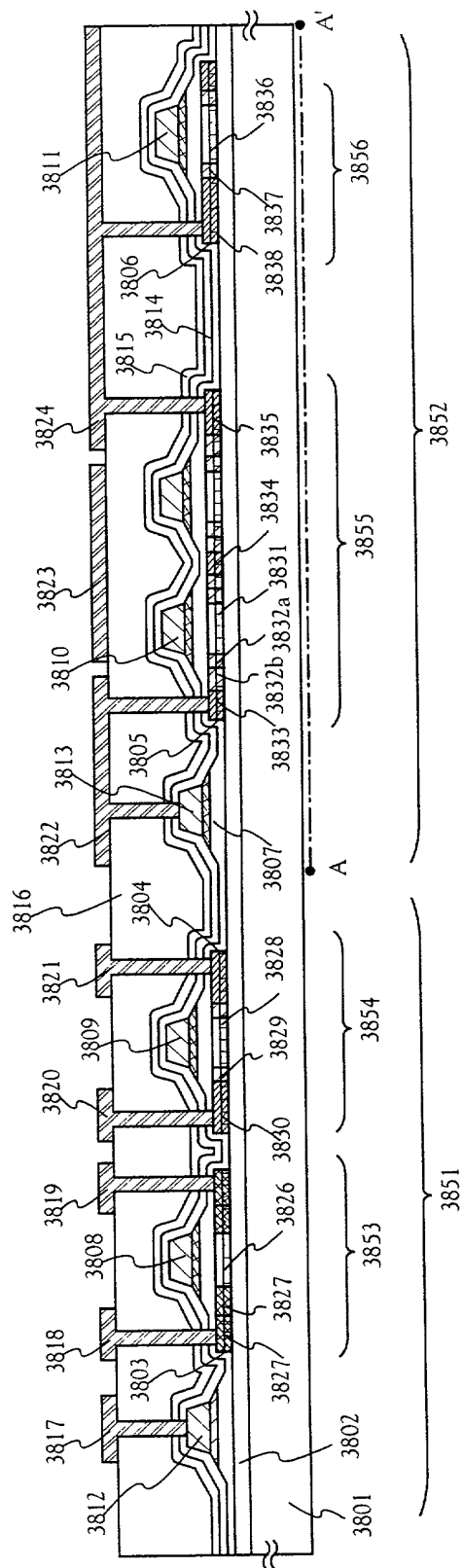


FIG. 43

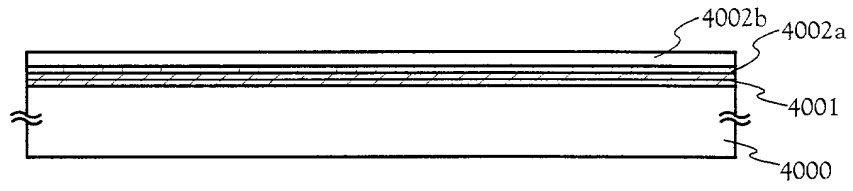


FIG. 44A

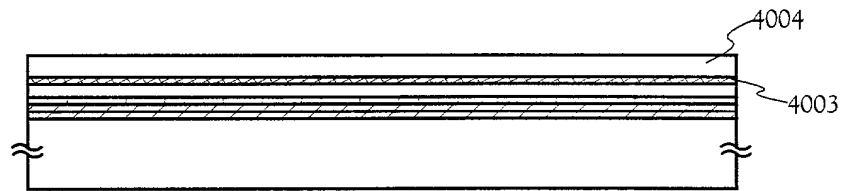


FIG. 44B

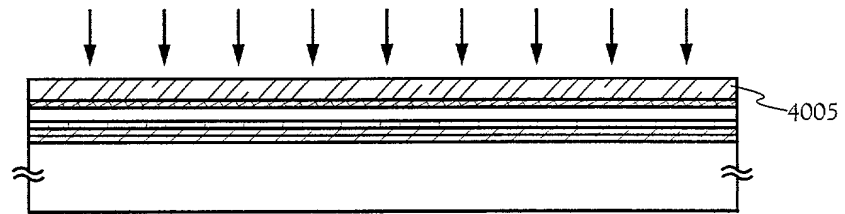


FIG. 44C

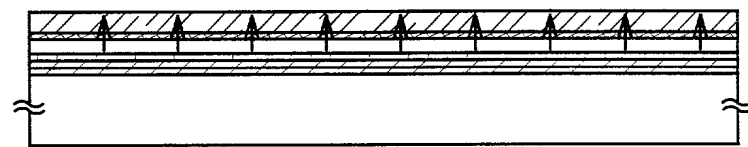


FIG. 44D

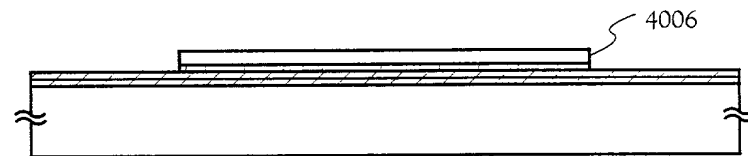


FIG. 44E

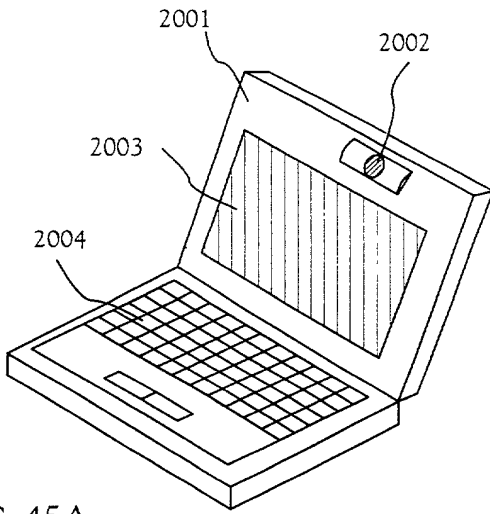


FIG. 45A

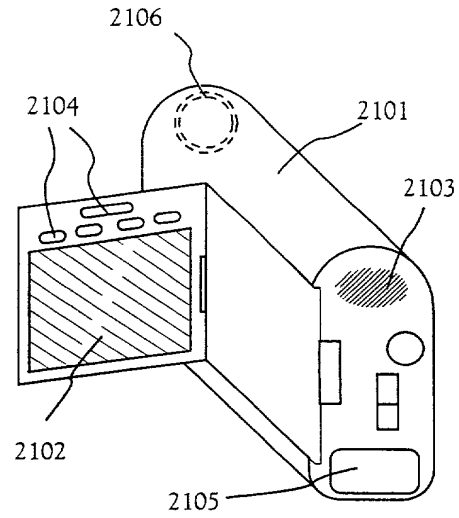


FIG. 45B

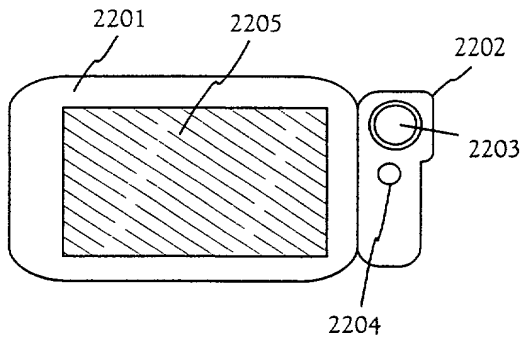


FIG. 45C

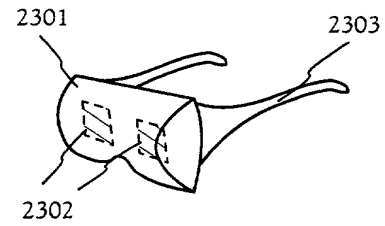


FIG. 45D

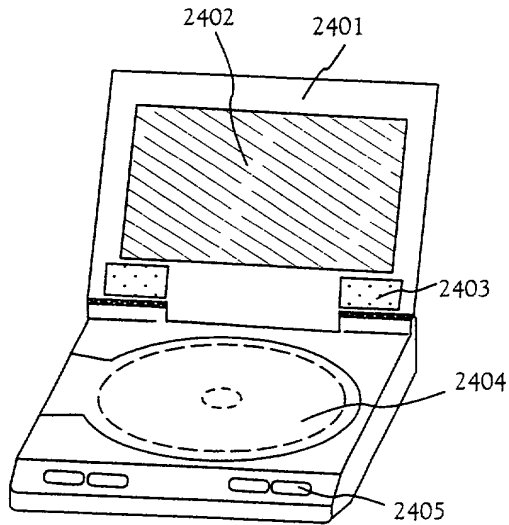


FIG. 45E

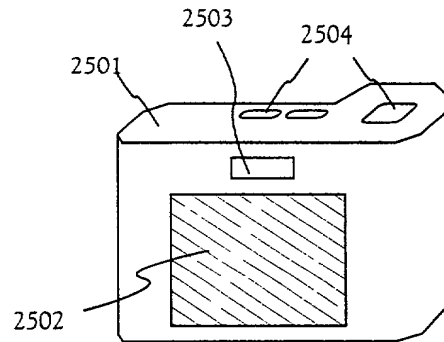


FIG. 45F

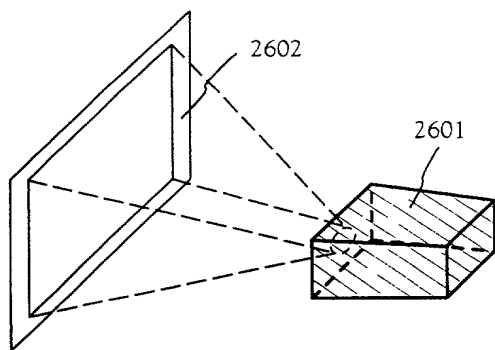


FIG. 46A

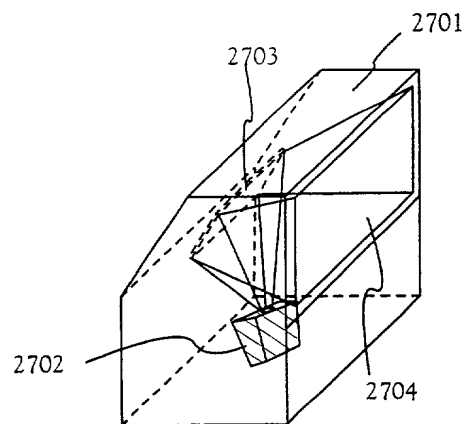


FIG. 46B

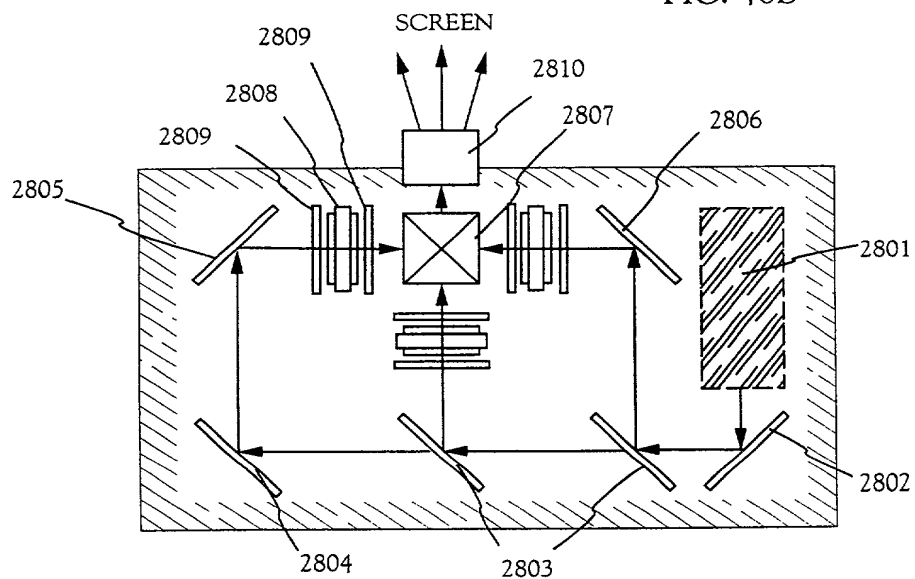


FIG. 46C

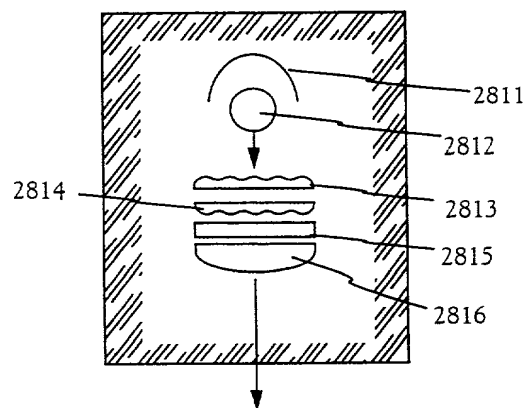


FIG. 46D

FIG. 46A

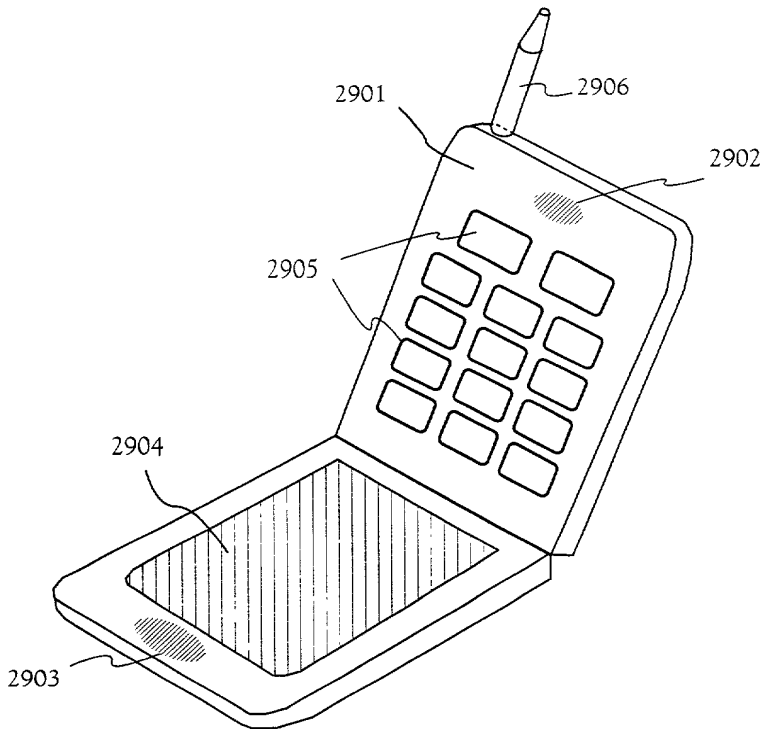


FIG. 47A

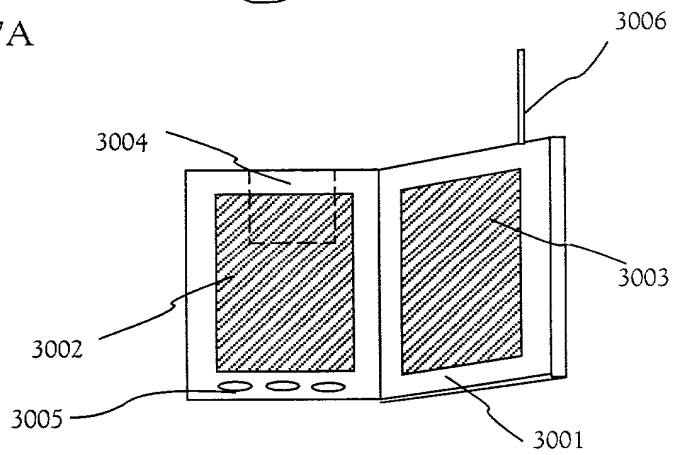


FIG. 47B

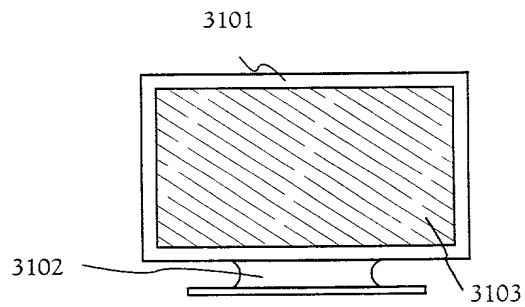


FIG. 47C